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# Recent Results from Diamond Detectors

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Ohio State University

On behalf of the RD42 Collaboration

*The help of my RD42 colleagues is gratefully acknowledged*

**13<sup>th</sup> International “Hiroshima”  
Symposium on the Development and  
Application of Semiconductor  
Tracking Detectors (HSTD13)**



**Vancouver, Canada**

Wosk Centre for Dialogue

**December 3-8, 2023**

# RD42 Collaboration (2023)



## The 2023 RD42 Collaboration

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# Outline



## Outline

- Diamond as a radiation detector
- 3D diamond pixel detectors
  - Concept and motivation
  - Results
- Rate Dependence of pCVD diamonds
- Conclusions and Outlook

Nucl. Instr. Meth. A **786** 97  
(2015)

ETH Thesis 28688 (2023)  
Micha Reichmann

<https://rd42.web.cern.ch/rd42/publications/publications.html>

## Backup Slides

- Summary of RD42 radiation tolerance results

J. Phys. D: Appl. Phys. **52**  
465103 (2019)

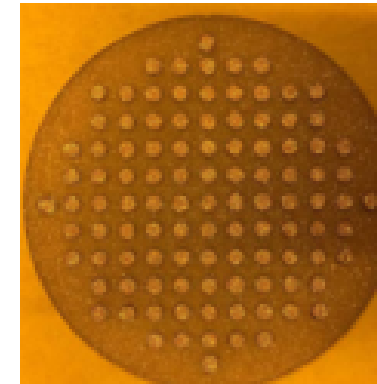
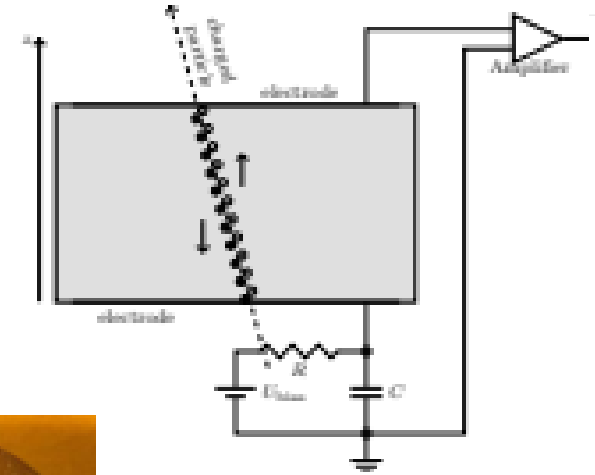
Sensors **20** 6648 (2020)

# Diamond as a radiation detector



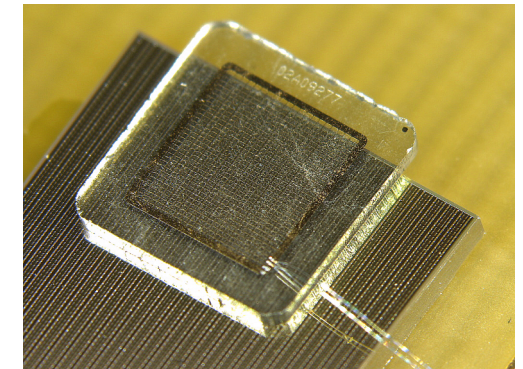
- Diamond detectors are operated as ionization chambers
  - 1 electron-hole pair generated per 13 eV ionizing energy loss
  - On average 36 electron-hole pairs per  $\mu\text{m}$  per MIP
  - Large (5.47 eV) bandgap ensures no thermal carriers
- Poly-crystalline material comes in large wafers
  - Wafers are grown 2-3x the final part thickness
  - Parts are cut out with a laser
  - Parts are thinned from the substrate side to the final thickness
  - RIE/ICP performed on both surfaces of all parts (critical)
  - Collection distance  $\sim 300 \mu\text{m}$  can be achieved on finished parts
  - Single-crystal sensors still confined to 4.5 mm x 4.5 mm size
- Devices can be made in any configuration
  - Pad, Strip, Pixel, 3D

Working principle



15 cm diameter pCVD diamond wafer

3D pCVD diamond sensor with pixel readout



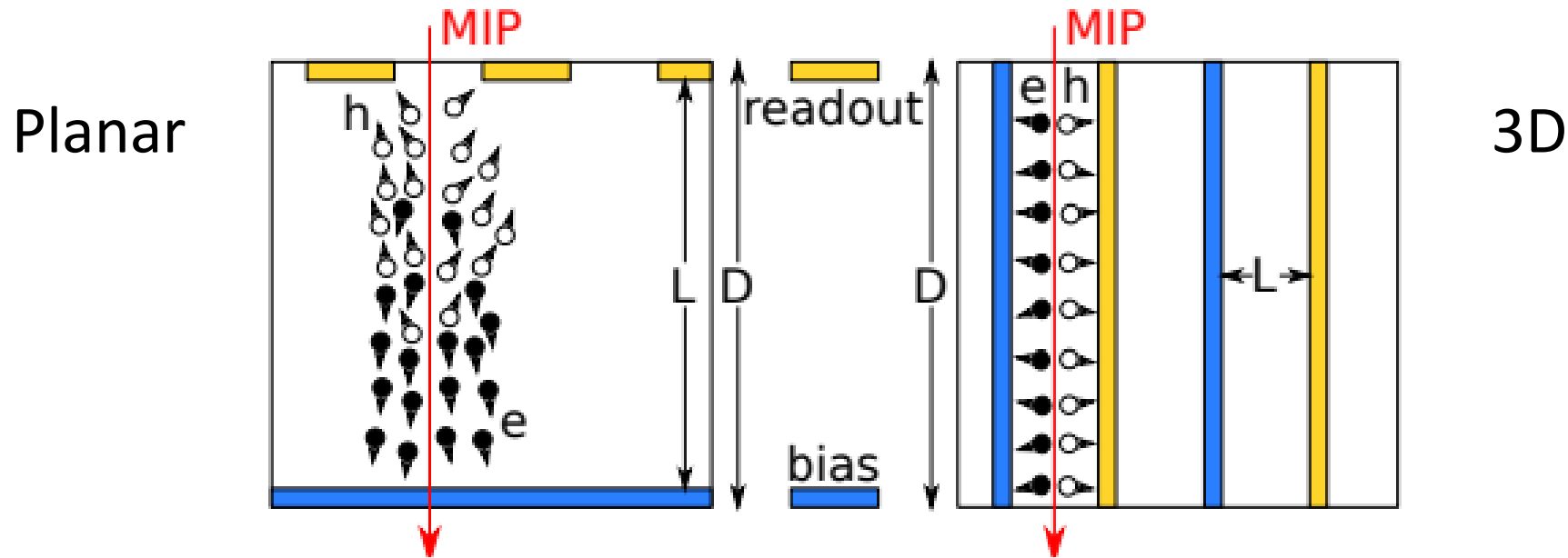


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# 3D Diamond Pixel Detectors

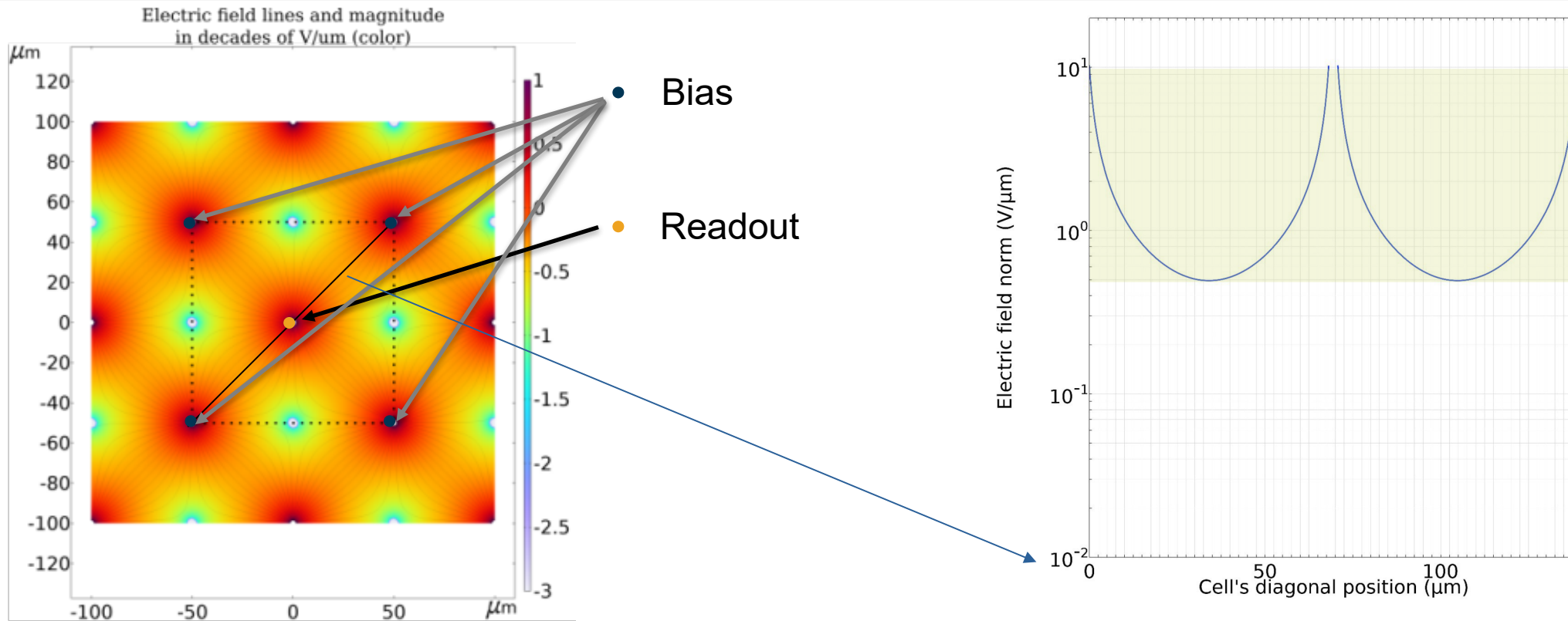
# Principle of a 3D detector

Parker et al., NIM A395 (1997)



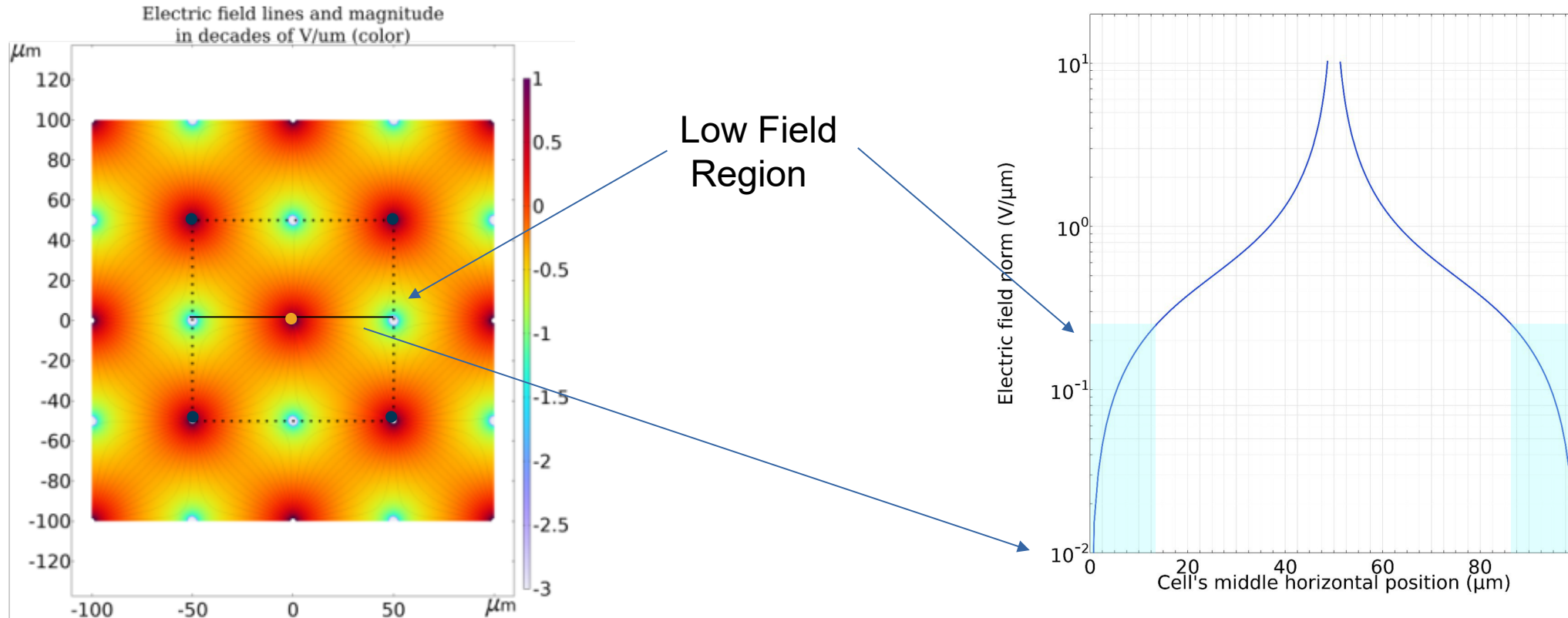
- After large radiation fluence all detectors become trap limited
  - mean drift distance in diamond  $\sim 26 \mu\text{m}$  after  $10^{16} \text{ n/cm}^2$
- In 3D detectors: bias and readout electrodes are inside the bulk detector material
- Same thickness  $D \rightarrow$  same amount of generated charge but 3D has shorter drift distance  $L$ 
  - $18 \mu\text{m}$  between the columns of a  $25 \mu\text{m} \times 25 \mu\text{m}$  cell
- In 3D detectors, collected charge is larger when drift distance  $<$  limited mean drift distance
  - However, low field regions are introduced

# Principle of 3D detector



- Simulation with 90 V bias voltage and periodic boundary conditions
  - 100  $\mu\text{m}$  x 100  $\mu\text{m}$  cell
- Electric field between  $\sim 0.5 - 10$  V/ $\mu\text{m}$  along the diagonal line

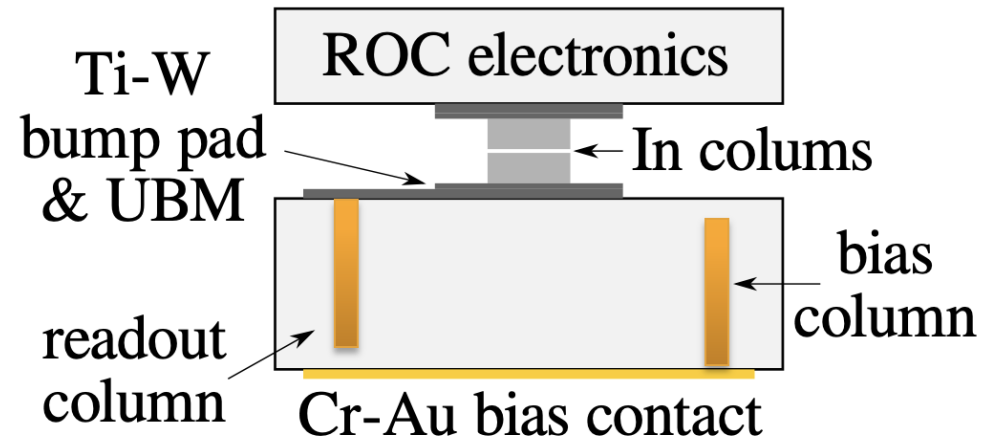
# Principle of 3D detector



- Simulation with 90 V bias voltage and periodic boundary conditions
  - 100 μm x 100 μm cell
- Electric field between ~0.01 – 10 V/μm along the horizontal line
  - Low field region (<0.25 V/μm) in between the electrodes and sizable (>25%)



# 3D diamond pixel detectors



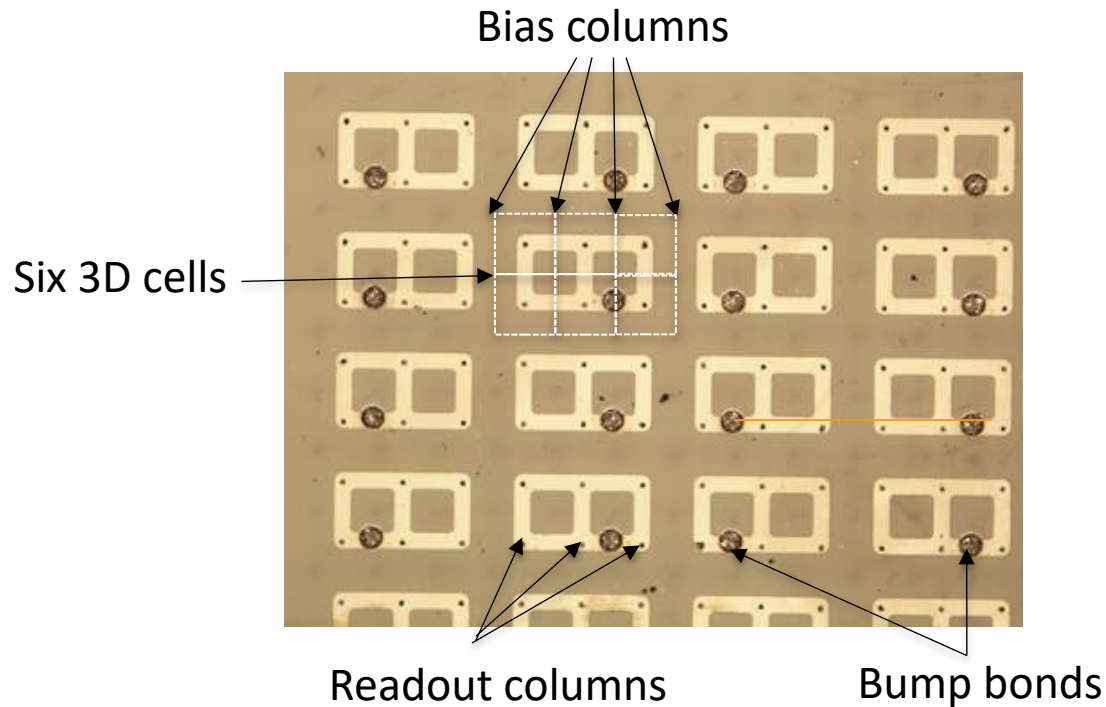
Two prototypes were built:

- One with  $50\ \mu\text{m} \times 50\ \mu\text{m}$  cells and one with  $100\ \mu\text{m} \times 150\ \mu\text{m}$  cells
- Bump bonding to CMS chip (PSI46dig2) at Princeton (Indium without reflow)
- Both readout and bias columns have a small gap ( $\sim 15\ \mu\text{m}$ ) to the opposite surface
- Column diameter  $2.6\ \mu\text{m}$  ( $50\ \mu\text{m} \times 50\ \mu\text{m}$ )
- Laser drilling efficiency 99.7%

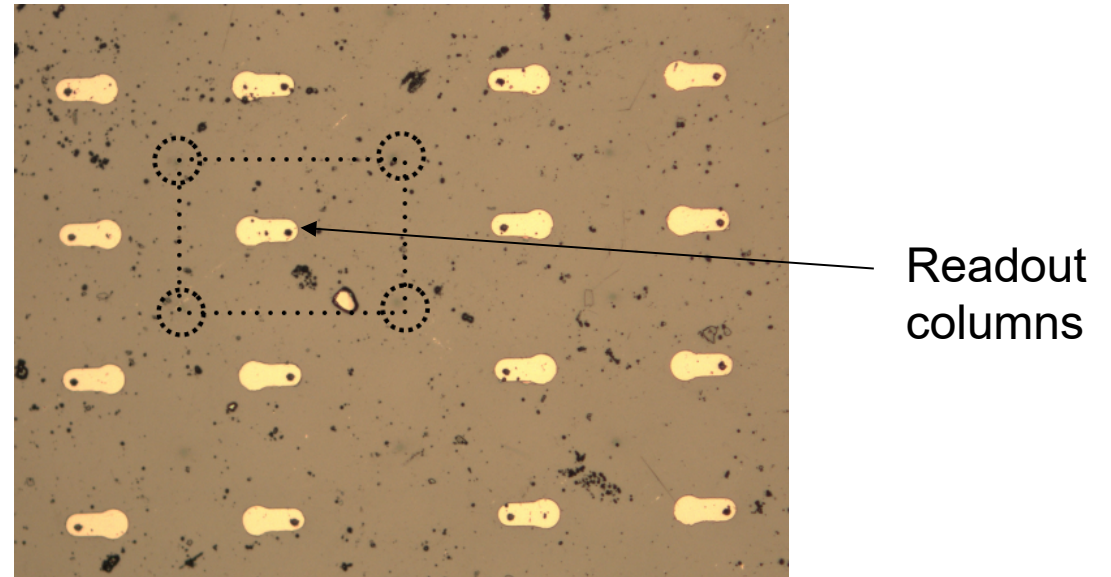
# 3D diamond pixel detectors



## Connection to readout columns with surface metallization



50  $\mu\text{m}$  x 50  $\mu\text{m}$  cells  
Readout side  
6 cells ganged to match the readout pitch

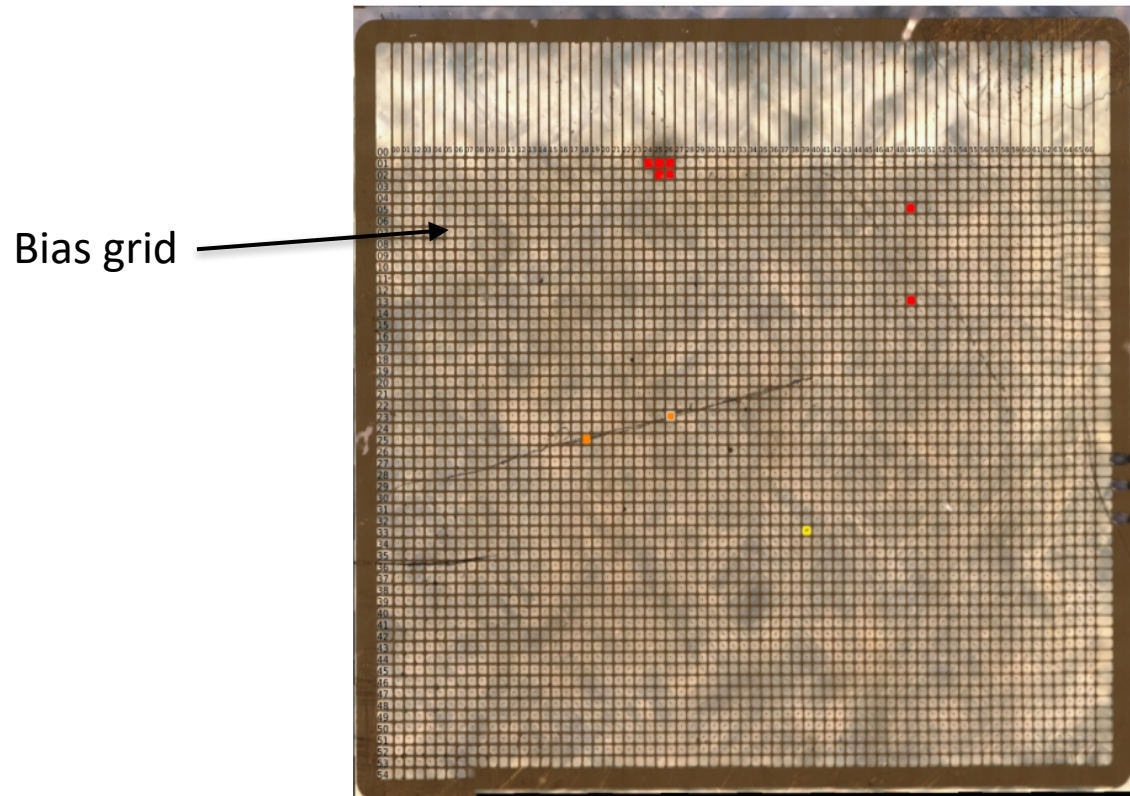


100  $\mu\text{m}$  x 150  $\mu\text{m}$  cells  
Readout Side

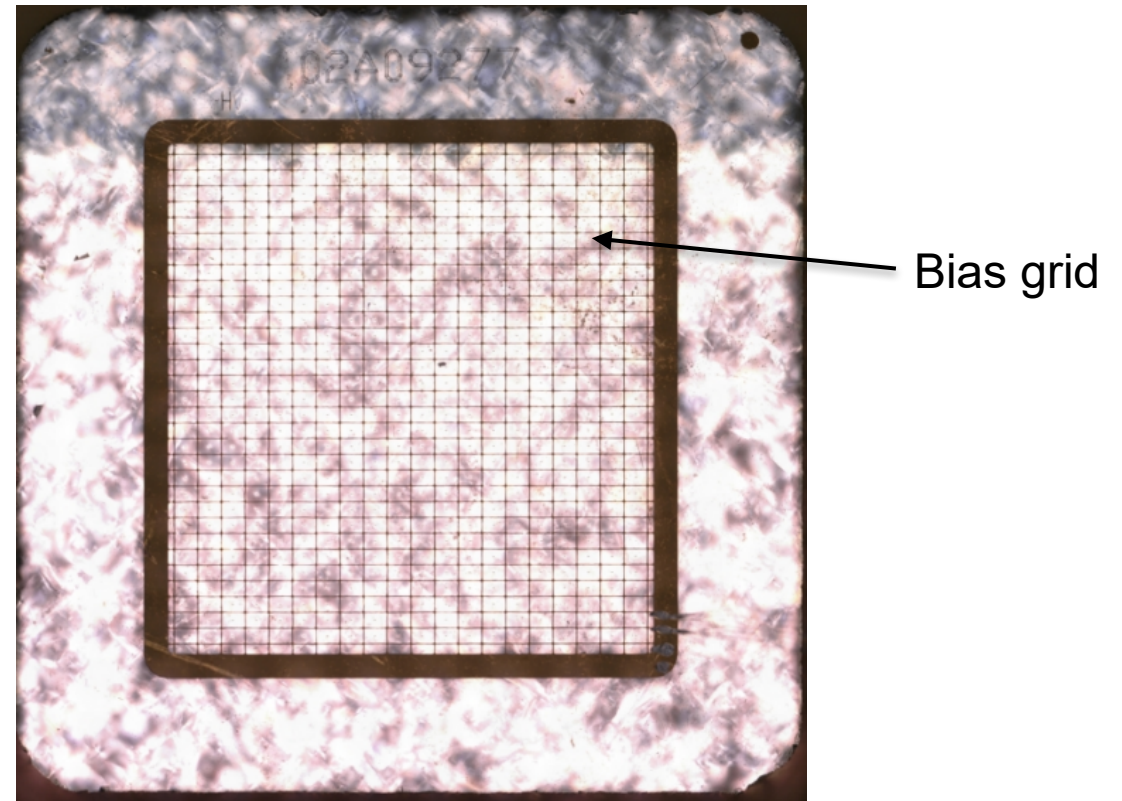
# 3D diamond pixel detectors



## Connection to bias columns with surface metallization



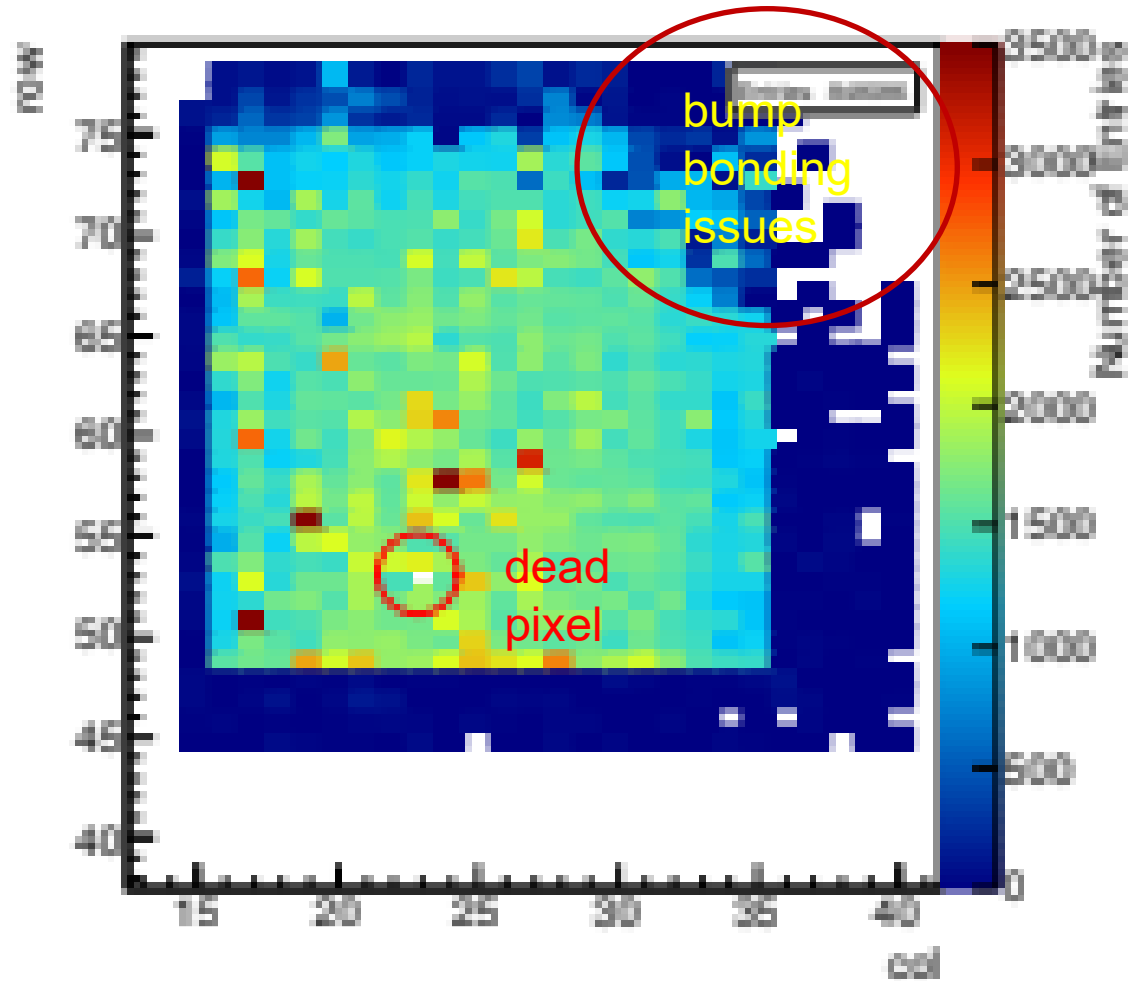
50  $\mu\text{m}$  x 50  $\mu\text{m}$  cells  
Bias side



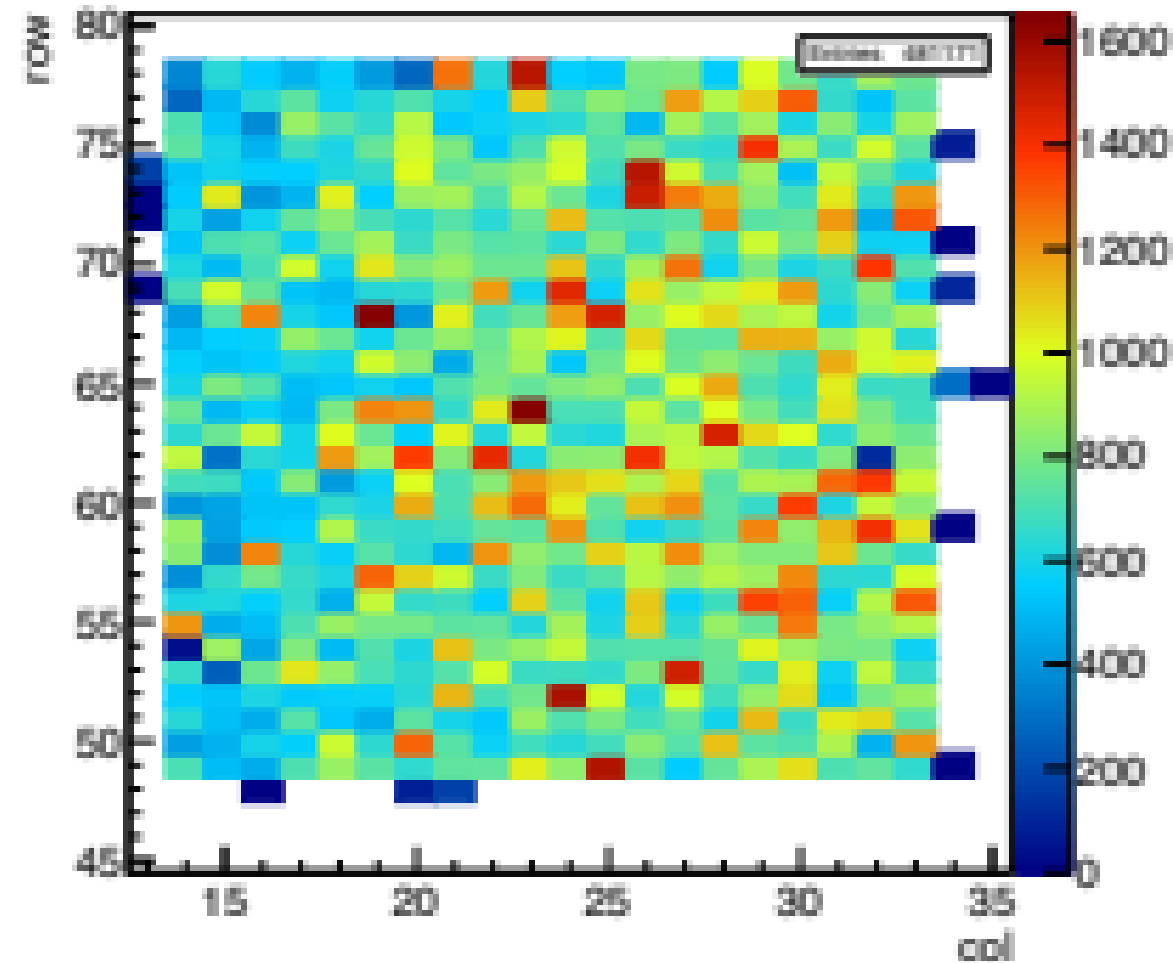
100  $\mu\text{m}$  x 150  $\mu\text{m}$  cells  
Bias Side

# Hit Occupancy

PSI Testbeam



50  $\mu\text{m}$  x 50  $\mu\text{m}$

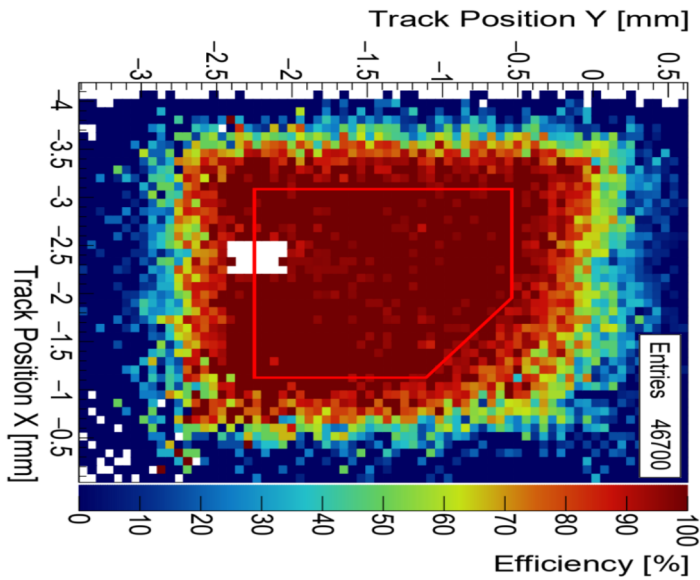


100  $\mu\text{m}$  x 150  $\mu\text{m}$

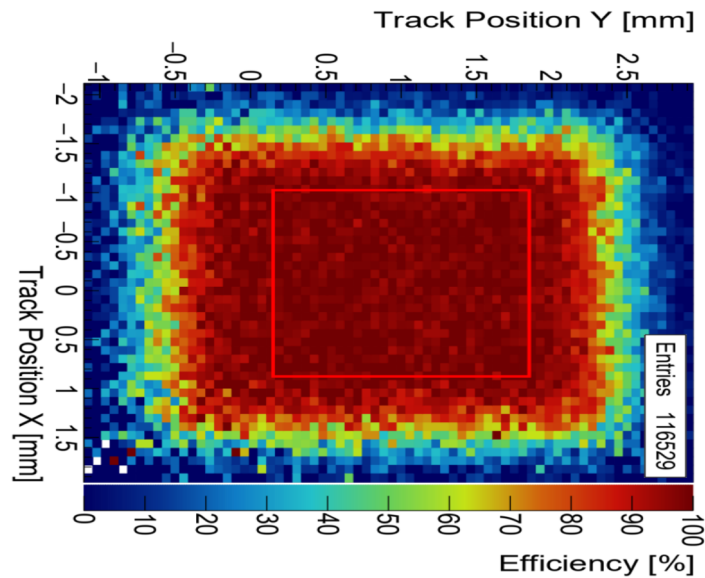
# Efficiency



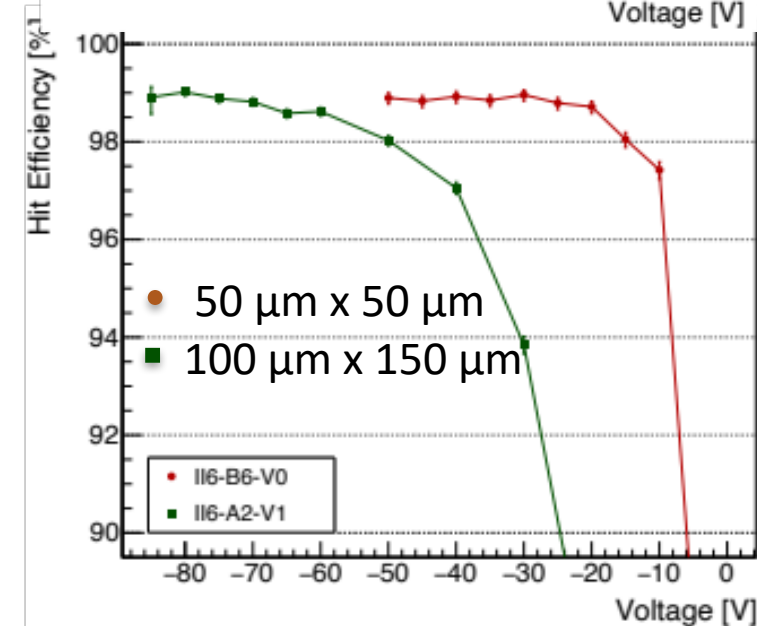
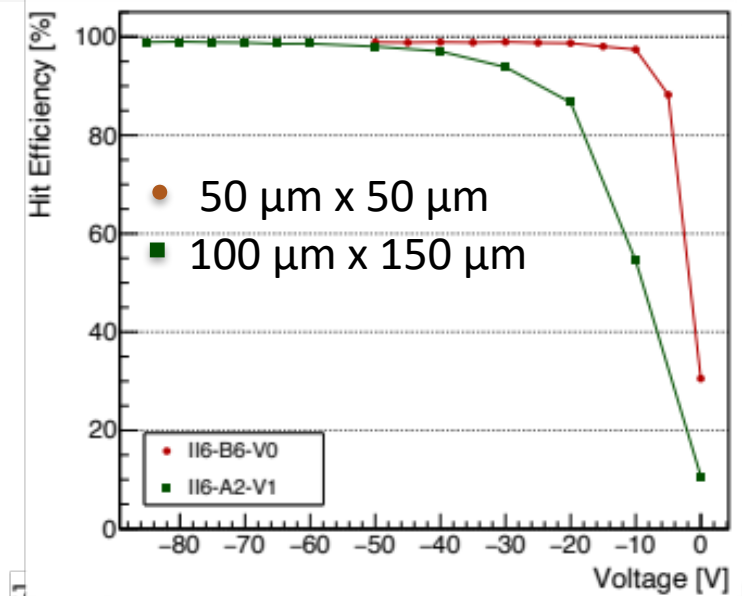
- Readout with PSI46dig v2.1-respin CMS chip
  - threshold  $\sim 2000$  electrons
- Testing at **PSI** (using 260 MeV  $\pi^+$  beam)
  - telescope resolution  $\sim 60 \mu\text{m}$  (multiple scattering)
- Fiducial selection avoids known problems



$50 \mu\text{m} \times 50 \mu\text{m}$

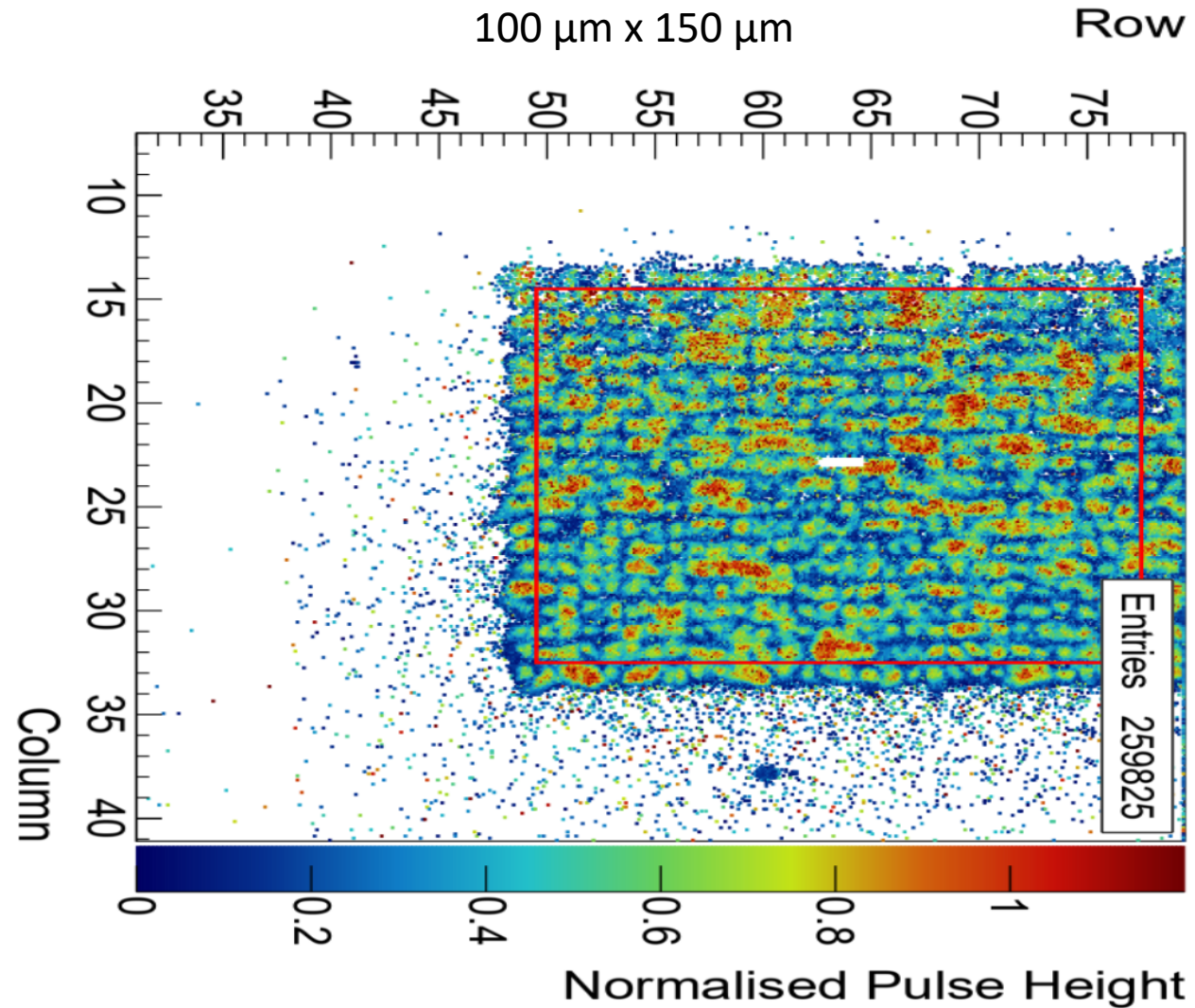
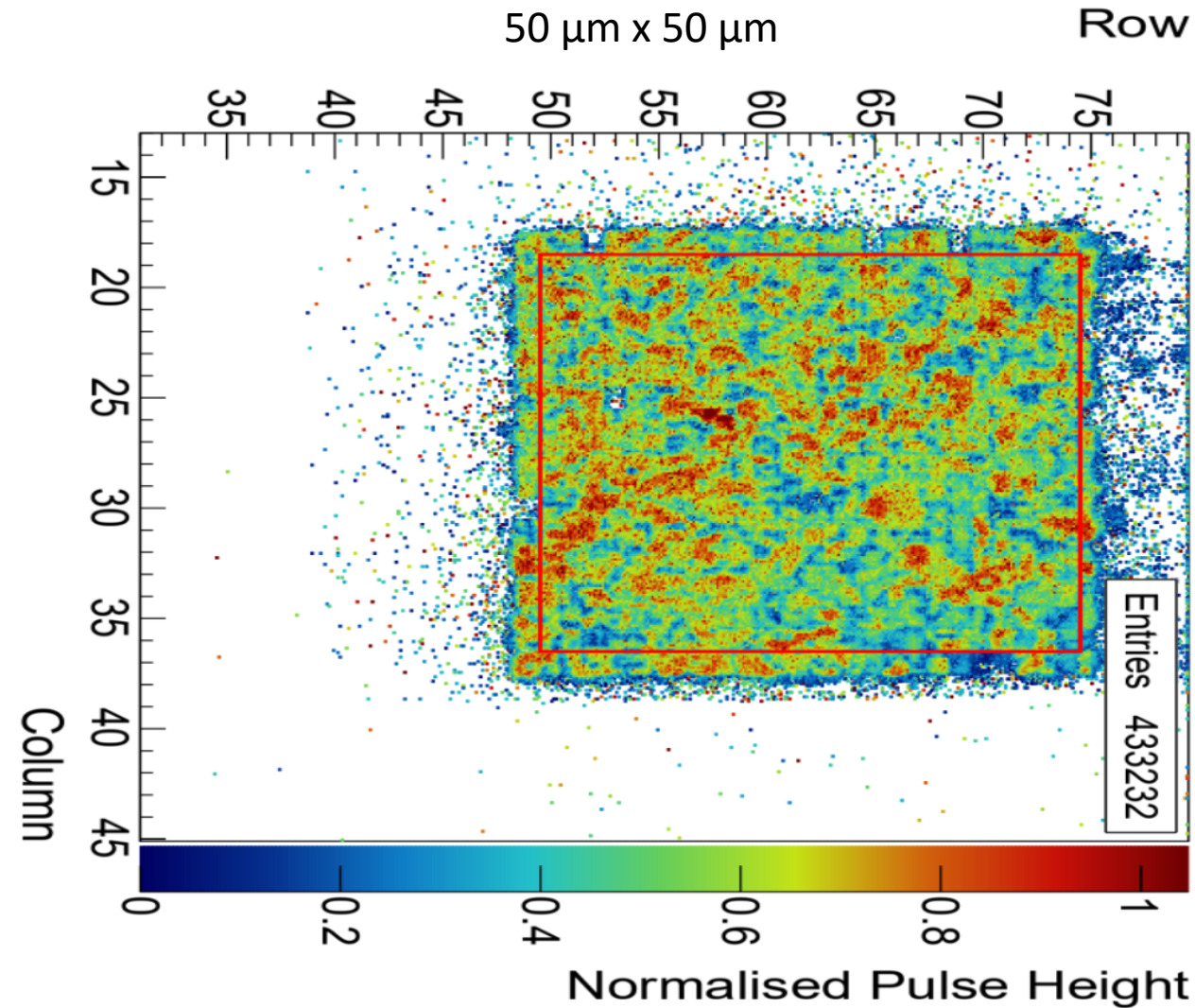


$100 \mu\text{m} \times 150 \mu\text{m}$



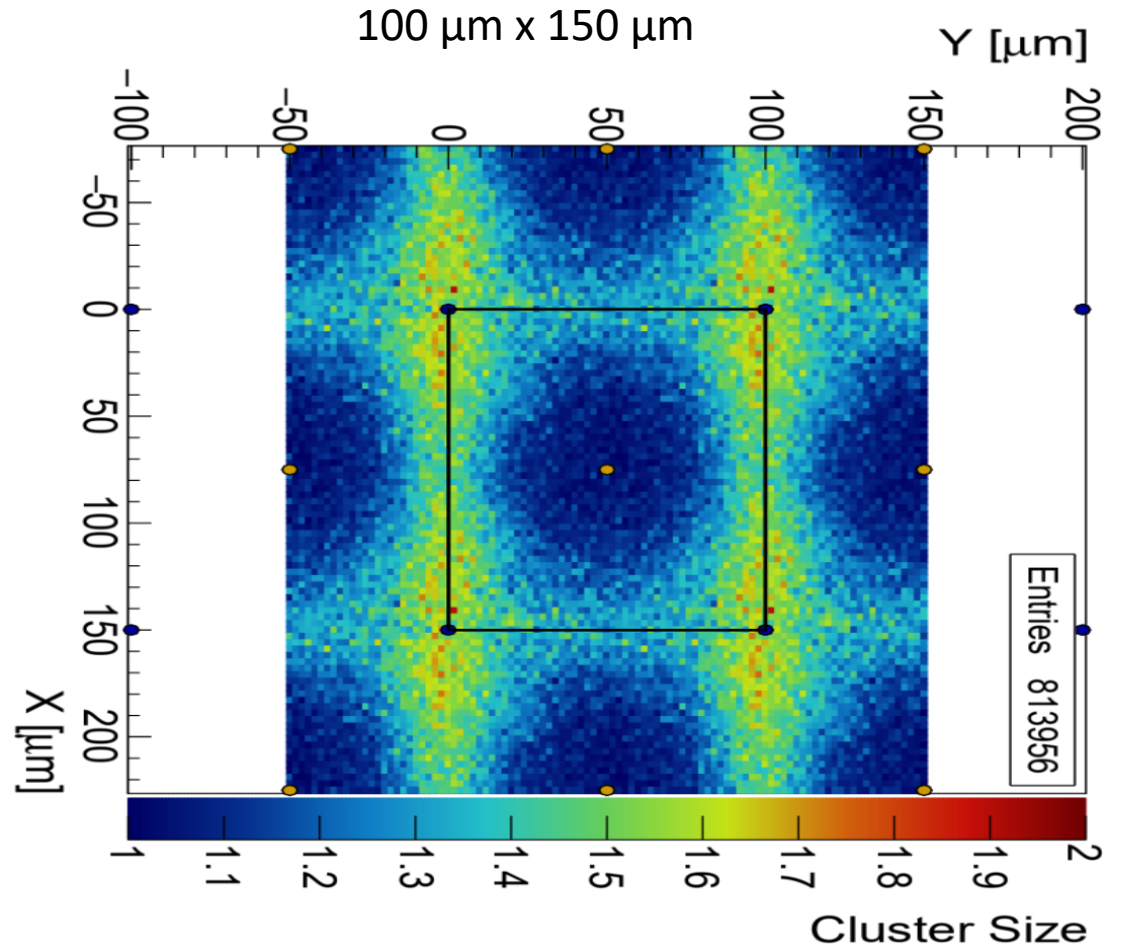
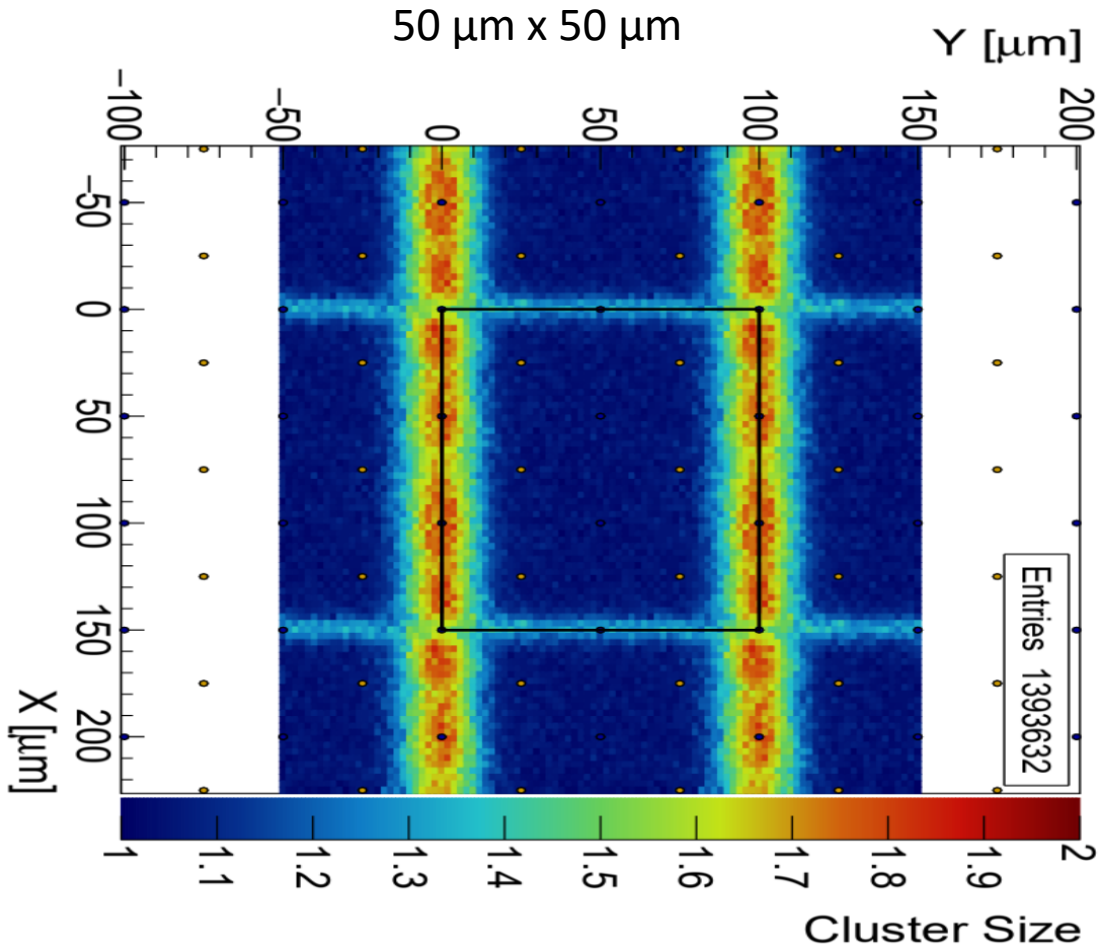
# Pulse Height vs Hit Position

CERN Testbeam



# In-cell Cluster Size

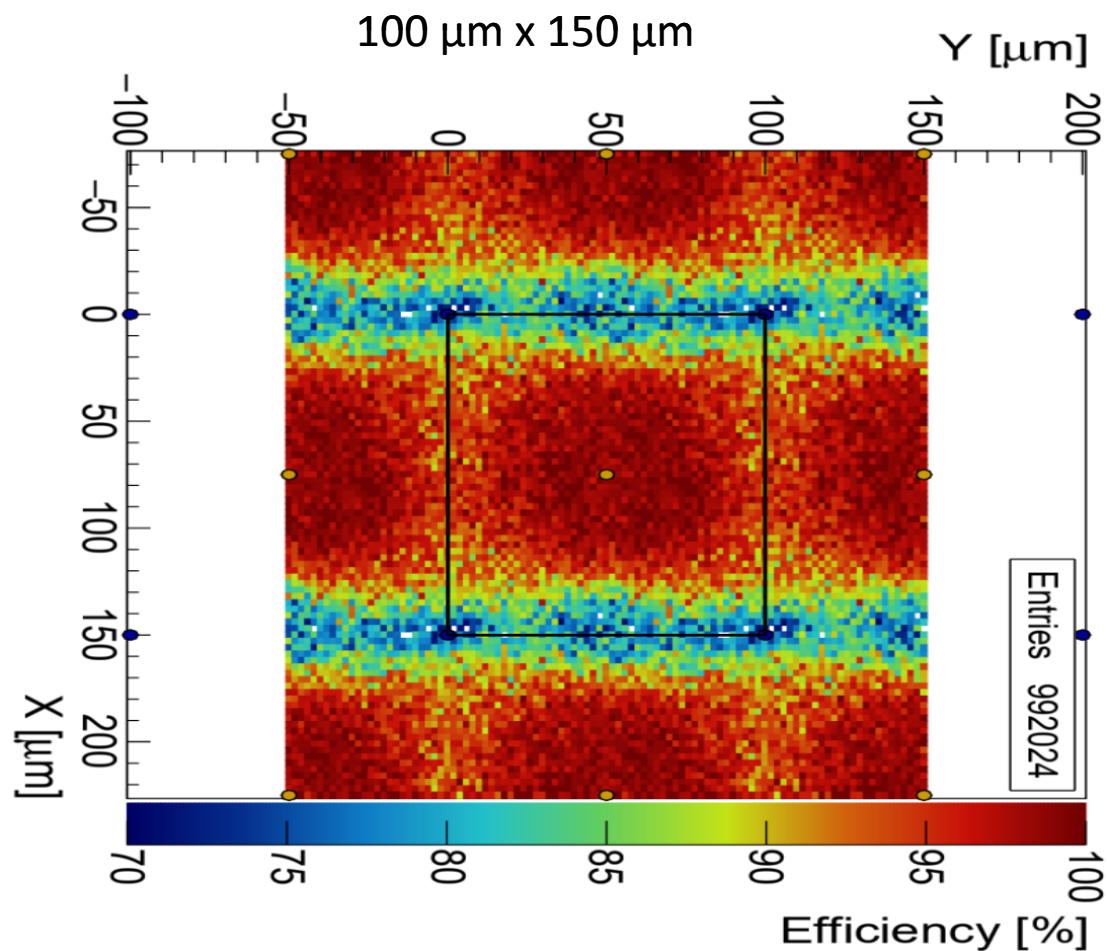
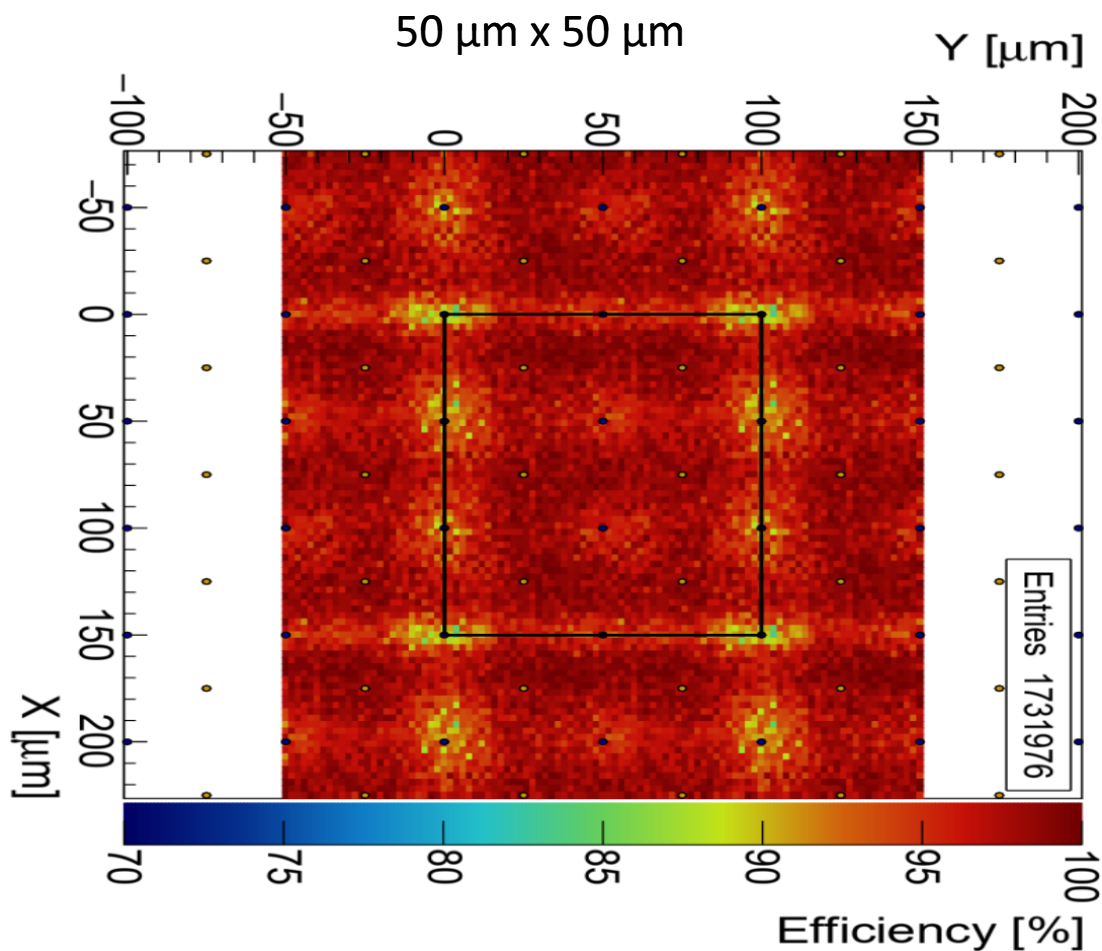
CERN Testbeam



- Bias
- Readout

# In-cell Efficiency

CERN Testbeam

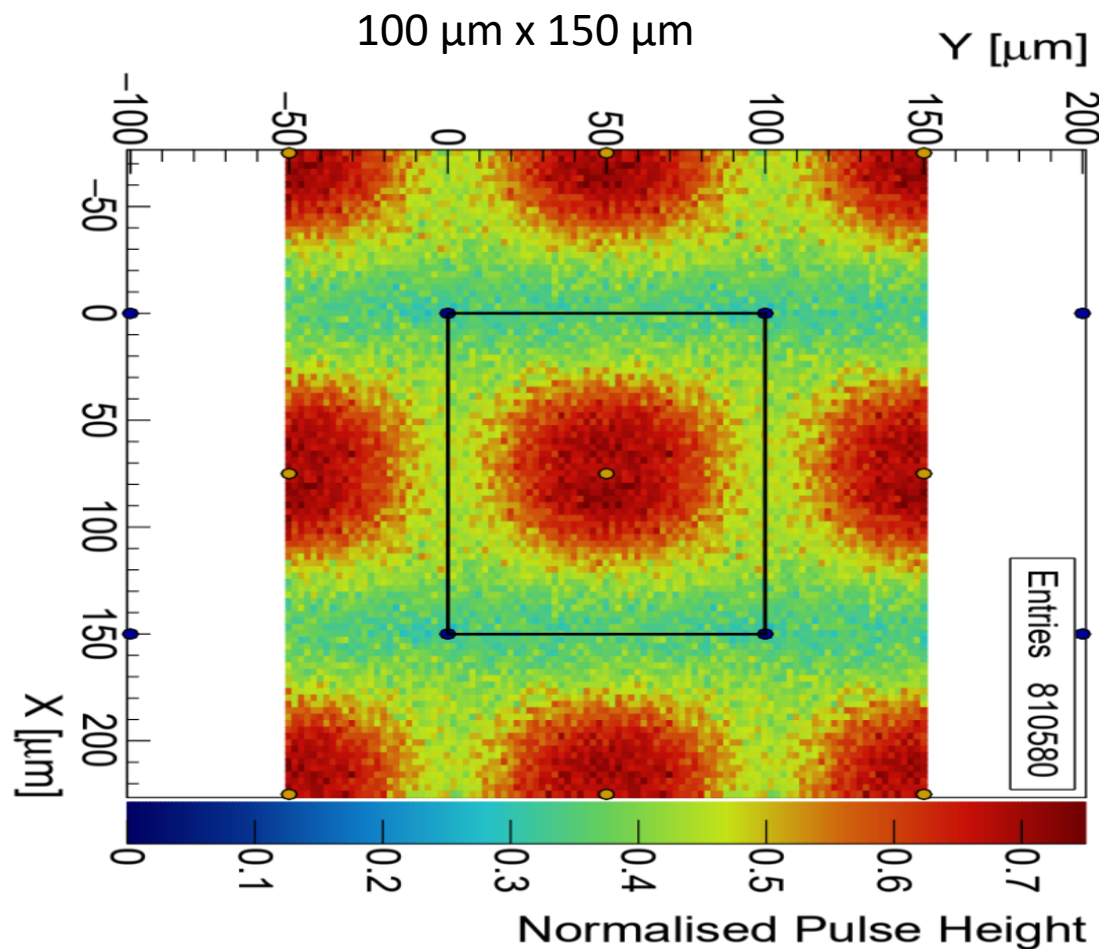
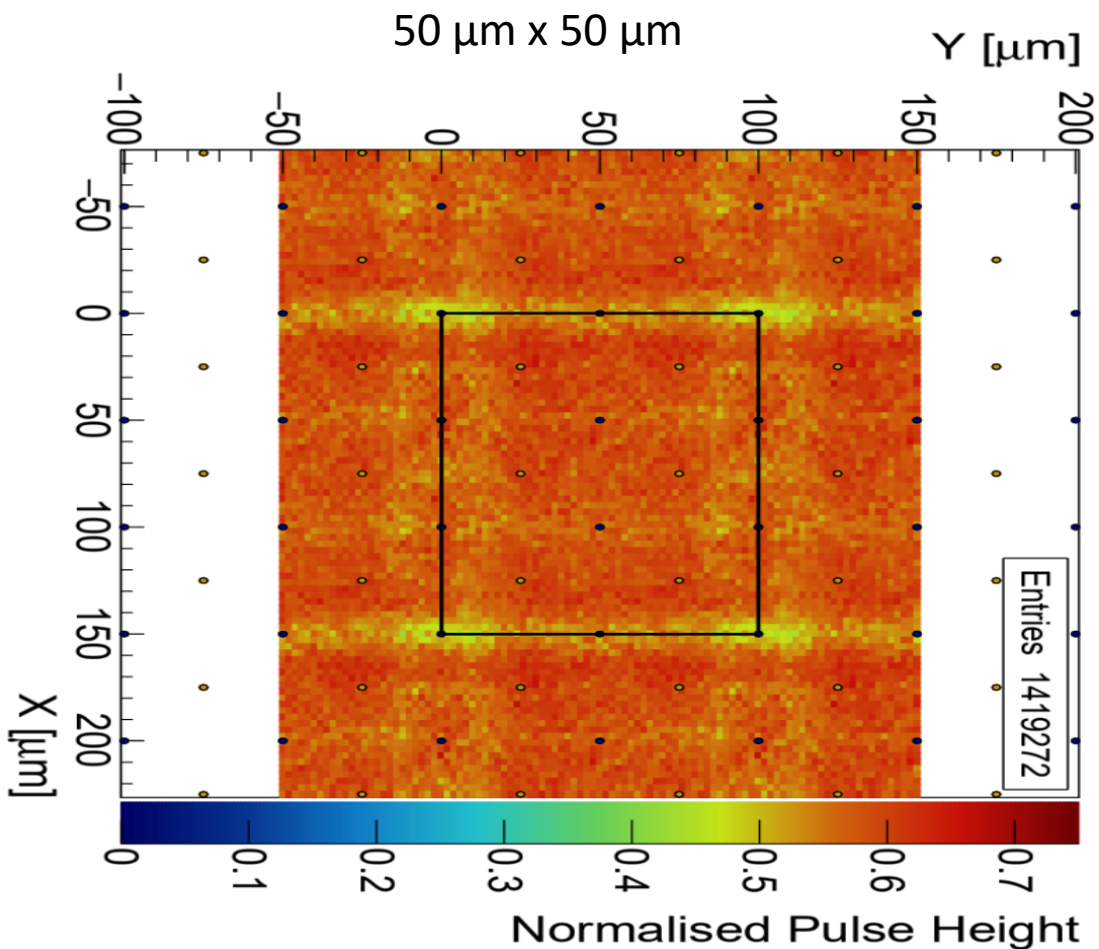


- Bias
- Readout



# In-cell Pulse Height

CERN Testbeam

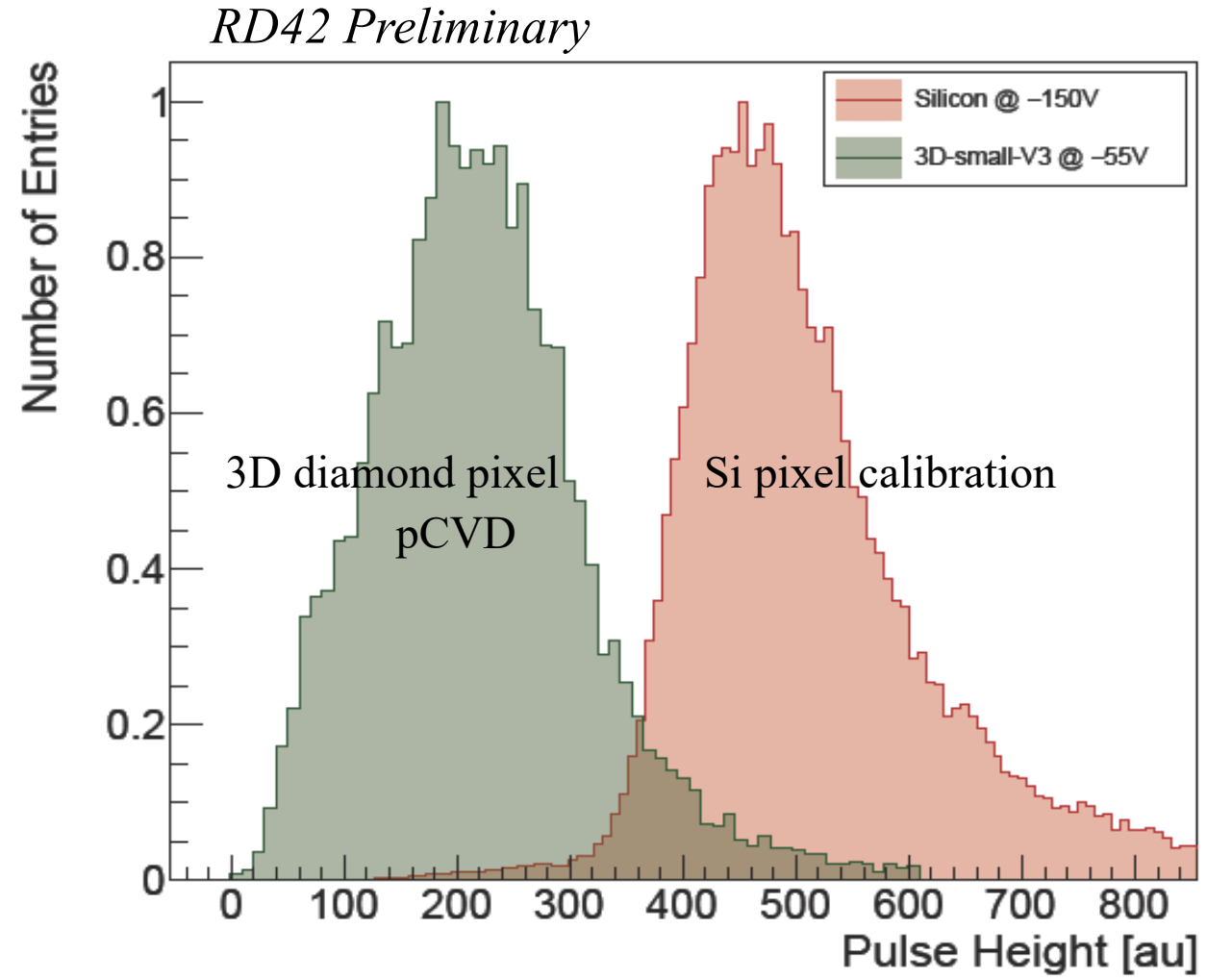


- Bias
- Readout

# Pulse Height Distributions



- 3D pCVD diamond collects >85% of charge
- efficiency in fiducial region: >99.2%
- In the 3D configuration, pCVD diamond looks single crystal like!





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# New Steps in Diamond Processing

# RIE/ICP Processing



Reactive Ion Etching/Inductively Coupled Plasma (RIE/ICP) Processing is a plasma processing step which can be used to “repair” surface issues.

This is particularly necessary in diamond processing since most manufacturers use mechanical processing (grinding) to finish “final” detectors.

These mechanical steps can create sub-surface damage as deep as 12  $\mu\text{m}$  beneath the surface. Such damage can become evident as visible surface defects, lower signals, larger leakage currents, HV breakdown, polarization and lower yield.

These effects can be mitigated with RIE/ICP processing.

# RIE/ICP Processing



- Visible surface defects

Before RIE/ICP

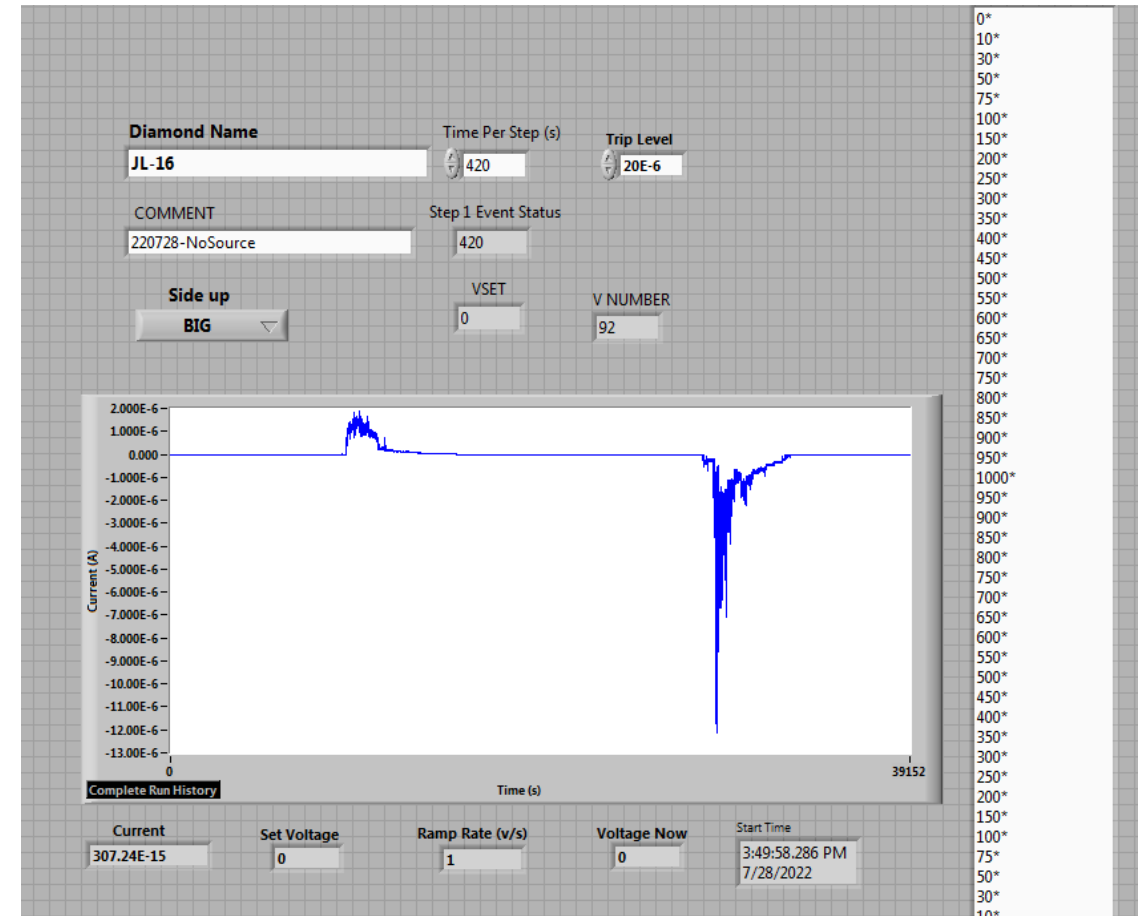
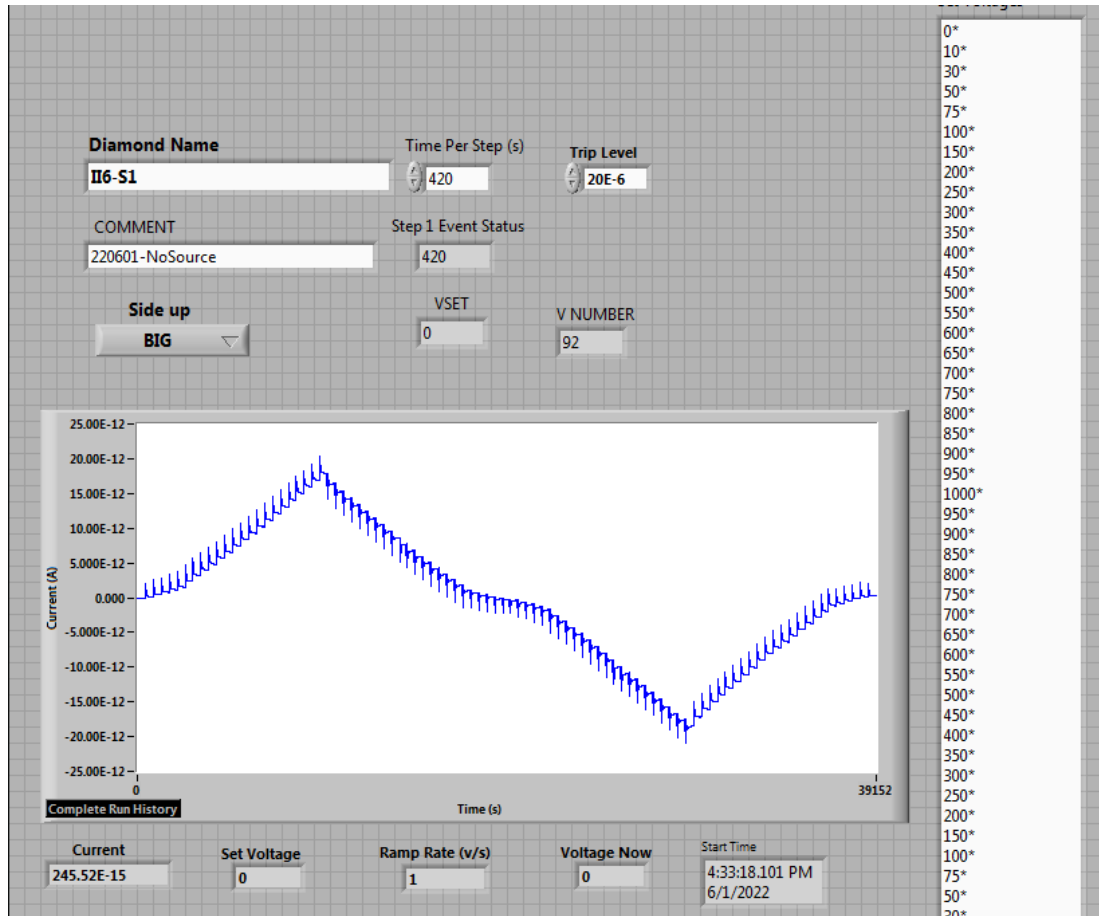


# RIE/ICP Processing



- Expected leakage currents (pA)

- Large leakage currents ( $\mu\text{A}$ )



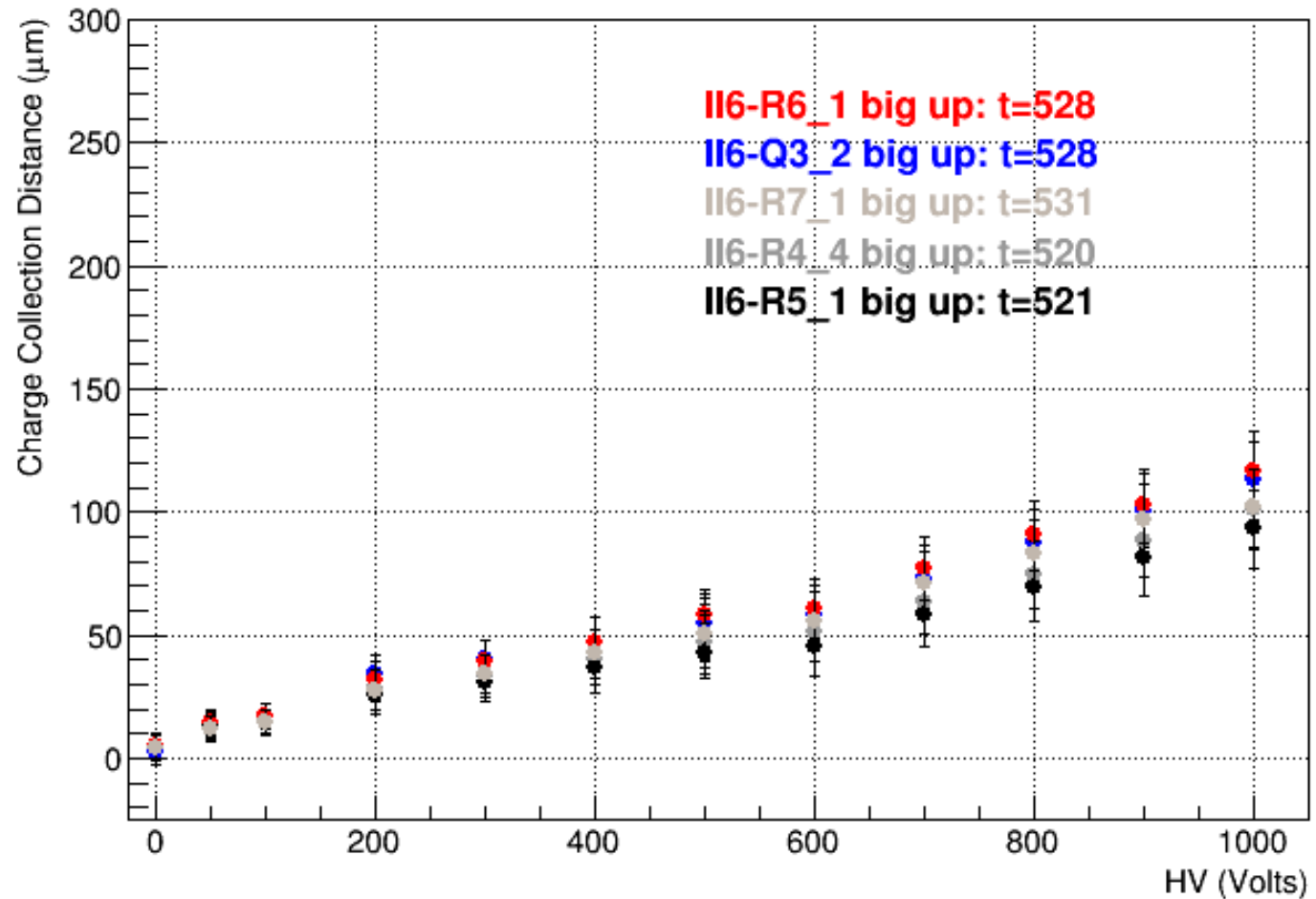
# RIE/ICP Processing



- Low signal size

Before RIE/ICP

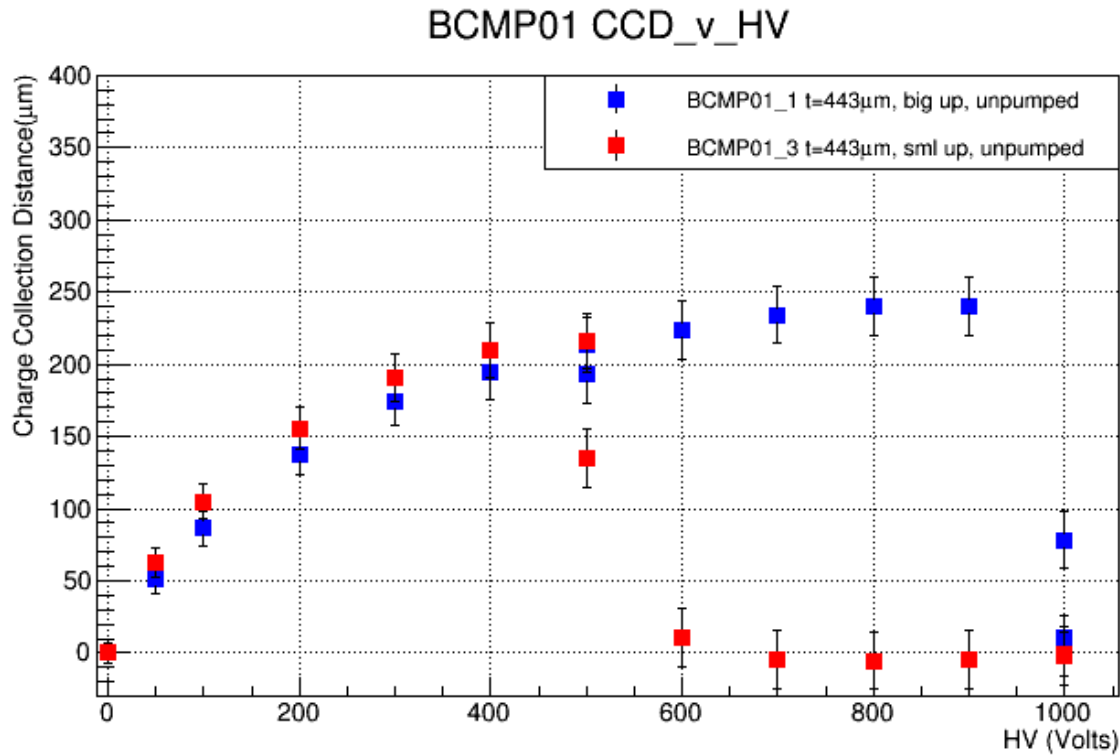
13B125: HV Curves



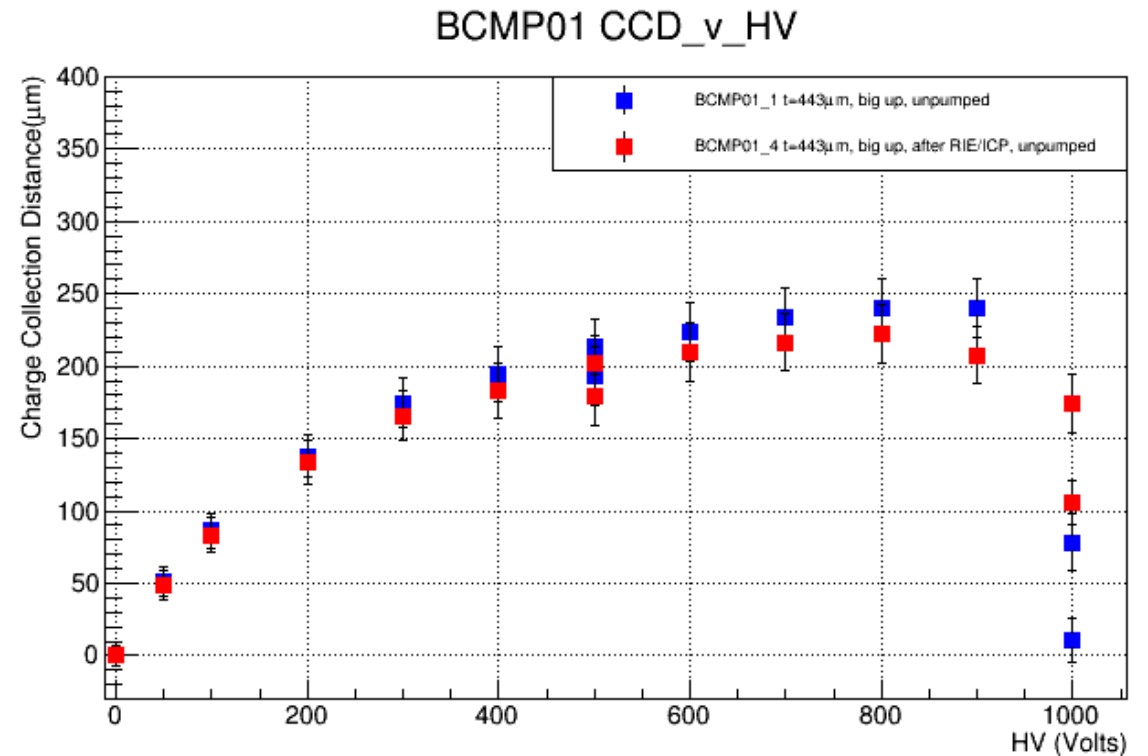
# RIE/ICP Processing



- HV Issues



Before RIE/ICP



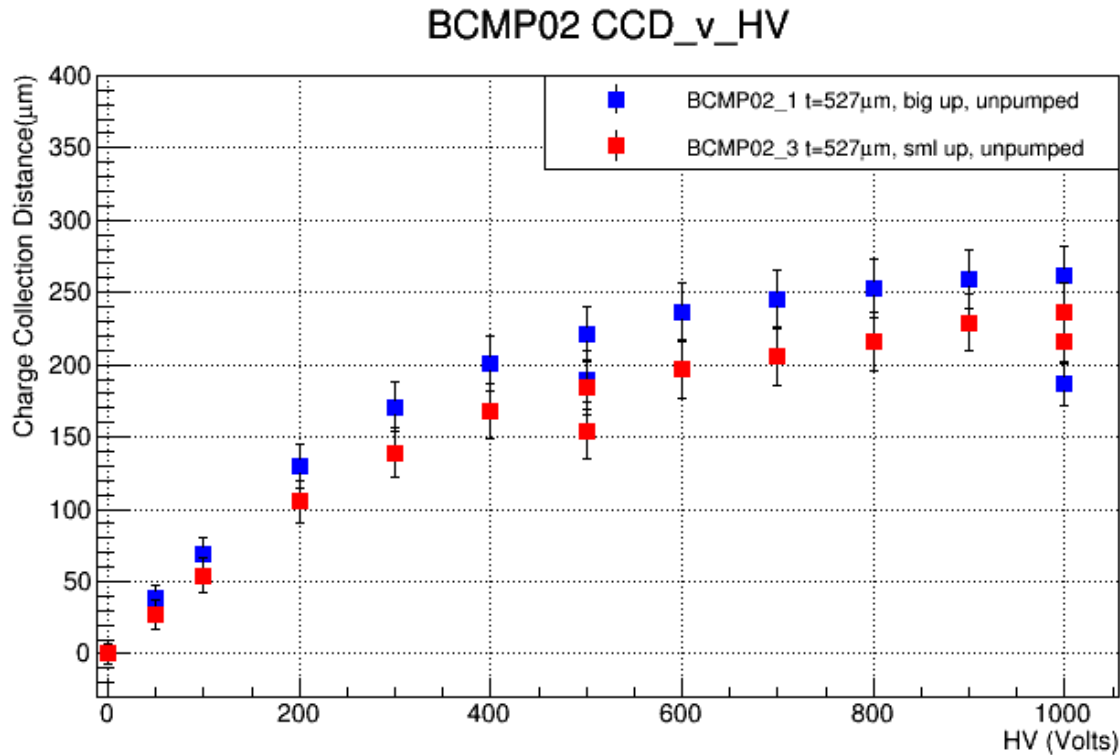
After RIE/ICP



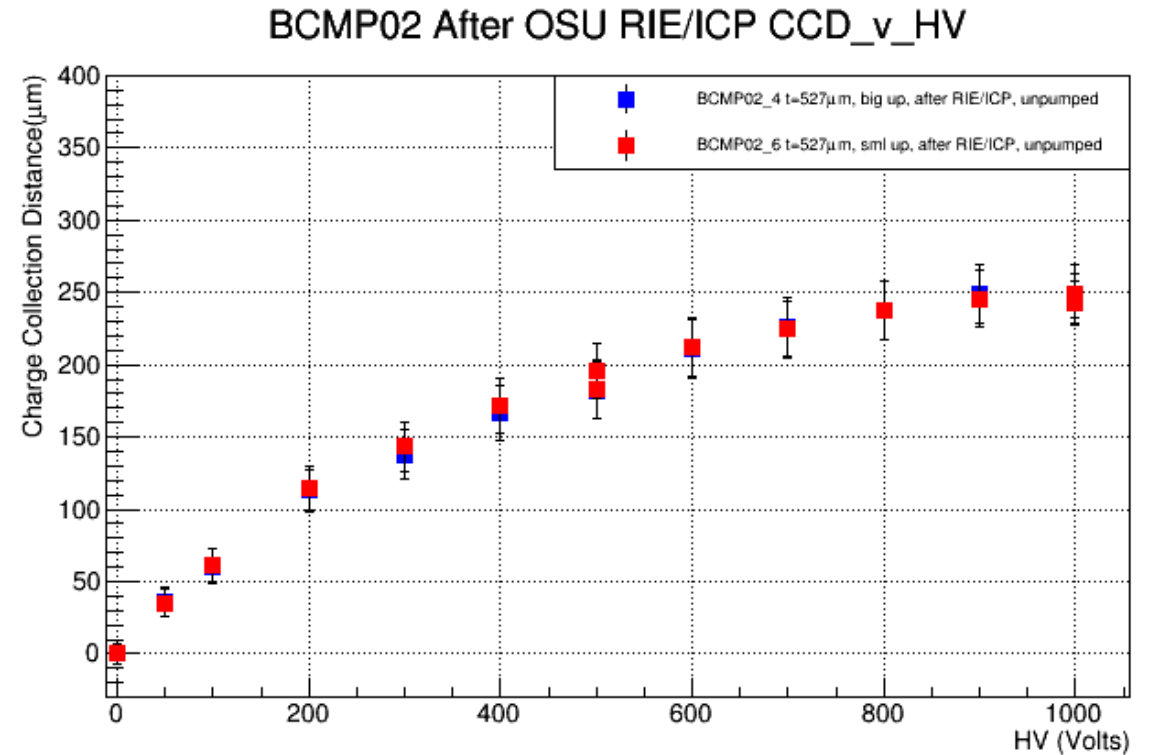
# RIE/ICP Processing



- Polarization Issues



Before RIE/ICP



After RIE/IC

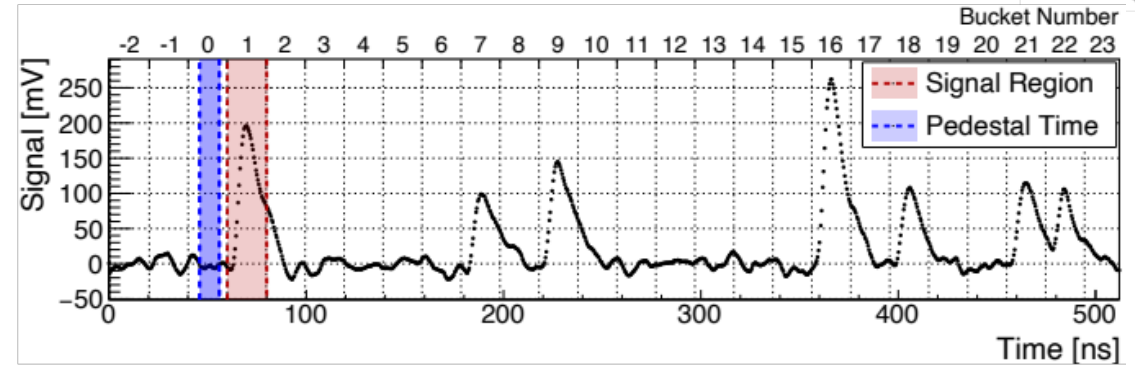
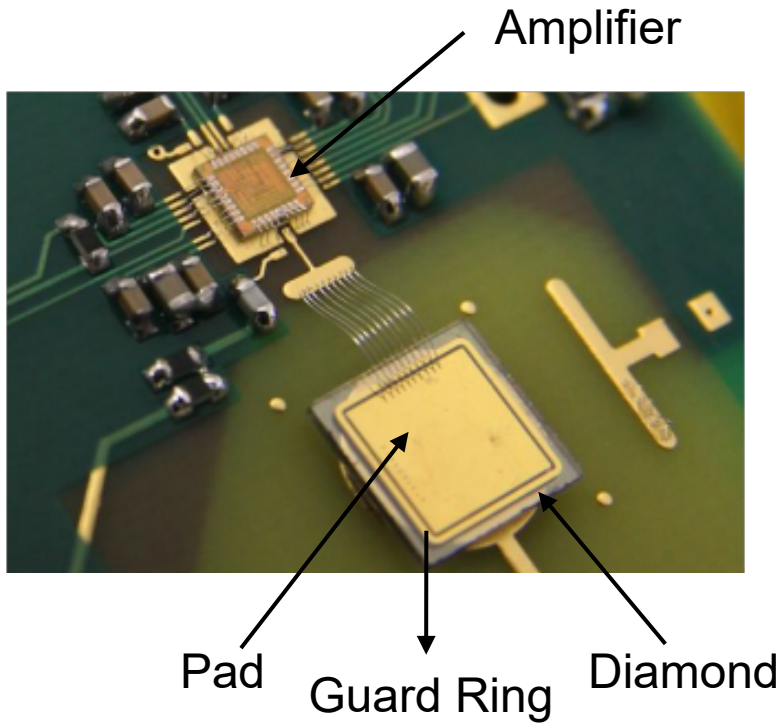


# Rate Dependence of pCVD Diamonds

# Rate dependence of pCVD diamonds



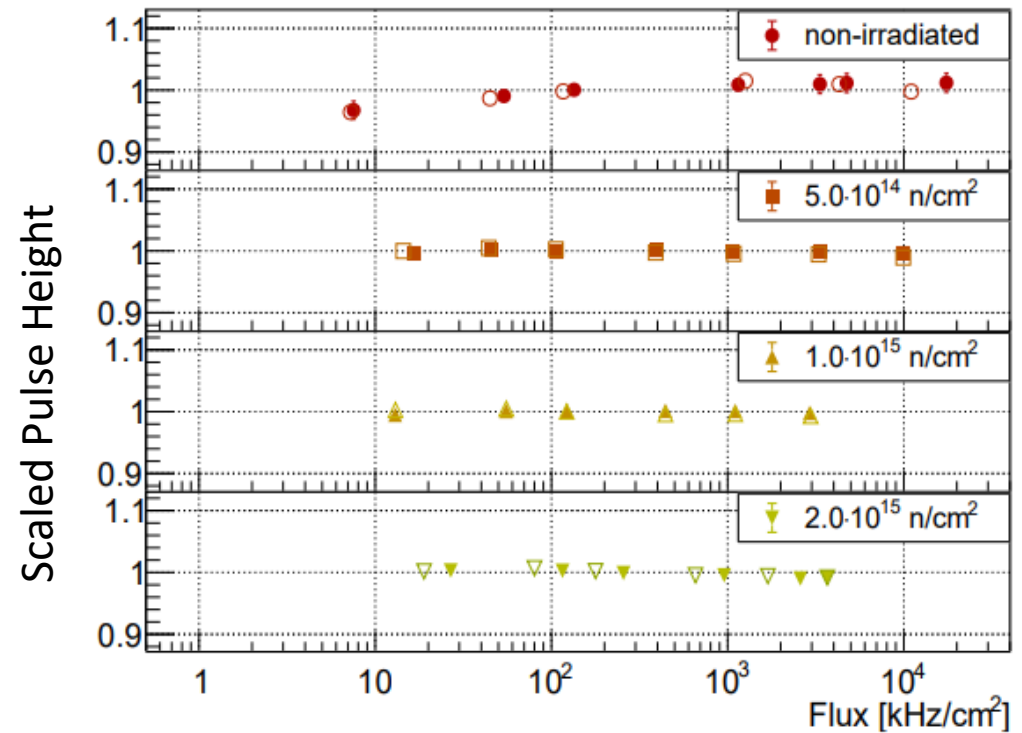
ETH Thesis 28688 (2022):  
M. Reichmann



No rate dependence observed in irradiated pCVD:

up to 20 MHz/cm<sup>2</sup>

up to 2x10<sup>15</sup> n/cm<sup>2</sup>



# Conclusions



- Two pCVD 3D pixel detectors with 50- $\mu\text{m}$  x 50- $\mu\text{m}$  and with 100- $\mu\text{m}$  x 150- $\mu\text{m}$  cells fabricated and compared
  - [M. Reichmann, Ph.D. Thesis 28688 ETH Zurich \(2022\)](#)
  - Laser drilling of  $\sim 2.6$   $\mu\text{m}$  diameter columns with  $>99.7\%$  efficiency achieved
  - Hit detection efficiency  $>99\%$  achieved with pixel electronics
  - 50  $\mu\text{m}$  x 50  $\mu\text{m}$  cells in pCVD diamond look very good; 100  $\mu\text{m}$  x 150  $\mu\text{m}$  cells are too large
  - 25  $\mu\text{m}$  x 25  $\mu\text{m}$  cells in pCVD diamond should give outstanding radiation tolerance
- RIE/ICP can mitigate many production issues
  - [In progress for ATLAS BCM'](#)
- No rate dependence for irradiated pCVD diamonds for 10 kHz -20 MHz/cm<sup>2</sup>, up to to  $2 \times 10^{15}$  n/cm<sup>2</sup>
  - [M. Reichmann, Ph.D. Thesis 28688 ETH Zurich \(2022\)](#)

# Conclusions and Future Plans



- Updated radiation hardness results of diamond to protons and fast neutrons up to fluences of  $2 \times 10^{16}$  protons/cm<sup>2</sup> plus a universal damage curve
  - [Journal of Physics D: Applied Physics, Volume 52, Number 46 \(2019\) \[DOI: 10.1088/1361-6463/ab37c6\]](#)
  - [Sensors, Volume 20, p. 6648 \(2020\) \[DOI: 10.3390/s20226648\]](#)

## Future Plans

- Irradiate and assess performance of 3D diamond detectors after fluences of  $10^{16}$  and  $10^{17}$  n/cm<sup>2</sup>
- Fabricate 25 μm x 25 μm 3D cells
- Scale up 3D column production using lasers
- Develop column etch process compatible with semiconductor industry



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# BACKUP



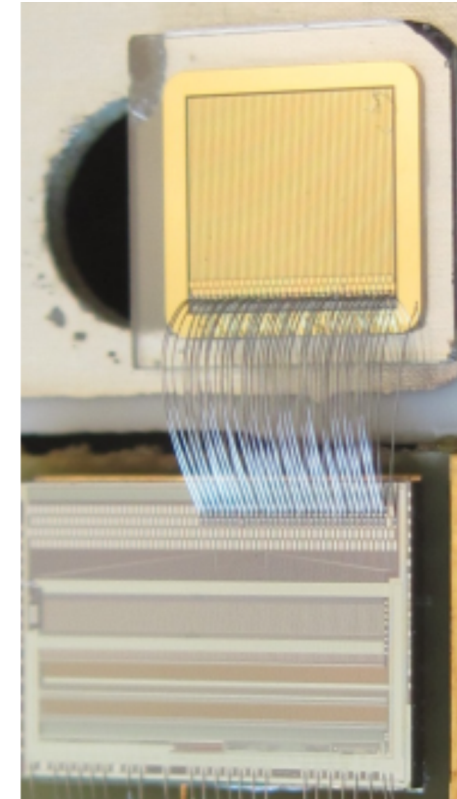
# Summary of RD42 Results on Radiation Tolerance

# Radiation tolerance of diamonds

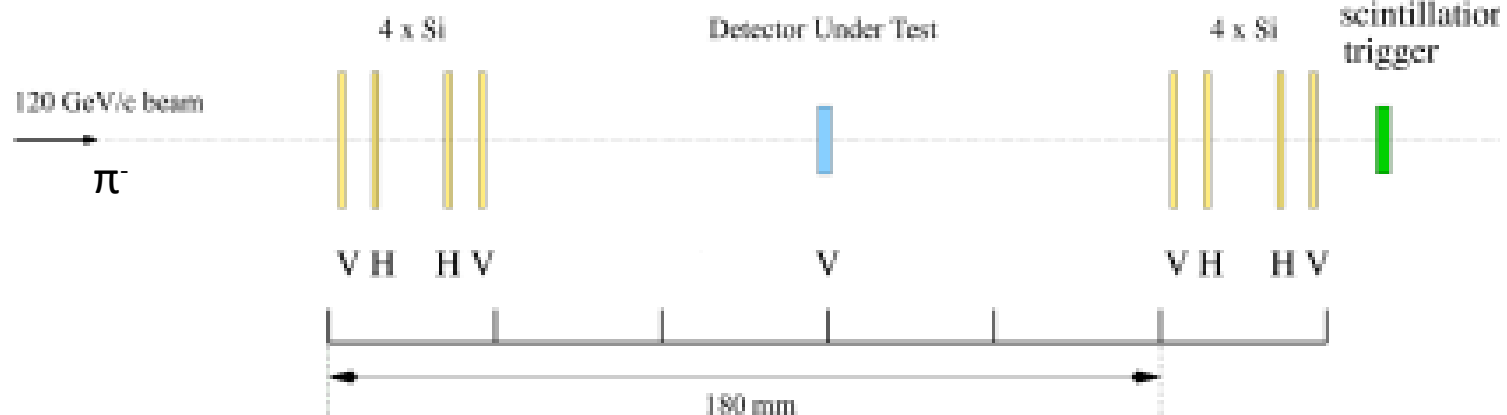


- Irradiate diamond samples with various particle species and energies
  - Re-metalize after each irradiation step to fabricate a strip detector
  - Readout with low ( $\sim 80$  electrons) noise VA2 chip
- Characterize irradiated devices in beam tests
  - Using hit prediction from telescope, collect charge in region of interest of up to 10 strips
  - Tracking precision at detector under test:  $\sim 2\text{--}3\ \mu\text{m}$

Diamond strip detector wire-bonded to a VA2 readout chip

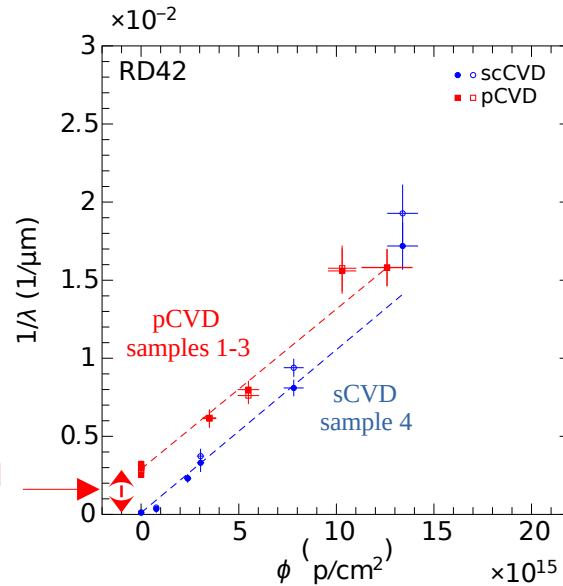
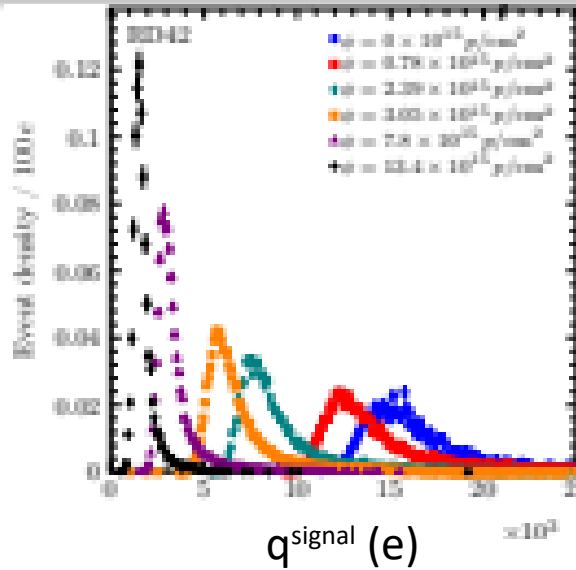


Schematic of the test assembly in CERN SPS H6A beamline





# Radiation tolerance of diamonds



- Measure pulse height as a function of irradiation

- Measure under both positive and negative bias
- Convert mean pulse height to mean drift length before immobilization by trapping/annihilation - “Schubweg” ( $\approx \mu E \tau$ )

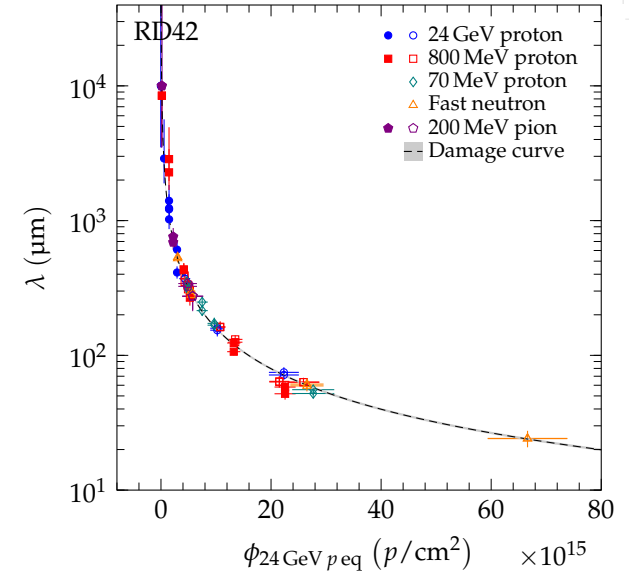
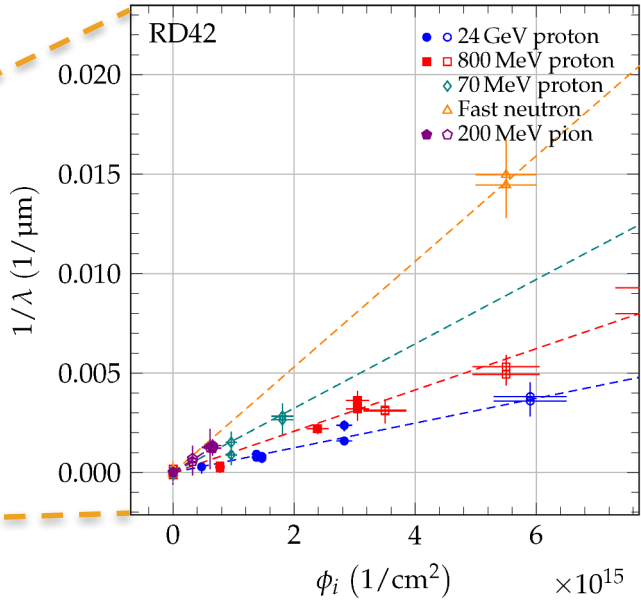
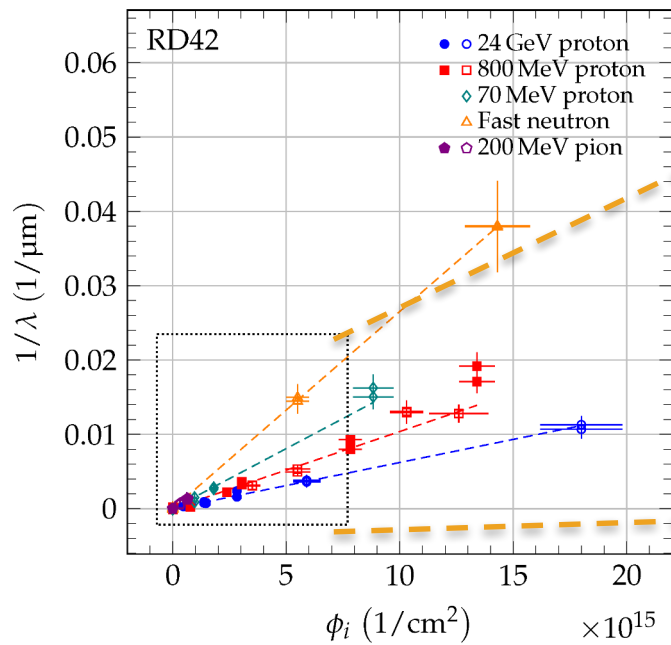
- Fit data with an empirical damage equation

- $n$  - number of traps,  $\lambda$  – Schubweg,  $k$  – damage constant,  $\phi$  - fluence

$$n = n_0 + k' \phi \quad \longrightarrow \quad \frac{1}{\lambda} = \frac{1}{\lambda_0} + k \phi$$

- The data for each sample are fit individually
- Poly has a shorter initial Schubweg due to a higher initial trap concentration (offset in  $1/\lambda$  at  $\phi=0$ )
- Slope for pCVD and scCVD are the same

# Summary of RD42 radiation tolerance results



Particle	Energy	Relative k
proton	24 GeV	1
	800 MeV	1.67+/-0.09
	70 MeV	2.60+/-0.29
pion	25 MeV	4.4+/-1.2
	200 MeV	3.2+/-0.8
fast neutrons		4.3+/-0.4

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